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Vertical GaN Power Electronics – Opportunities and Challenges

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U.S. DEPARTMENT OF
ENERGY | Energy Efficiency &
Renewable Energy
VEHICLE TECHNOLOGIES OFFICE



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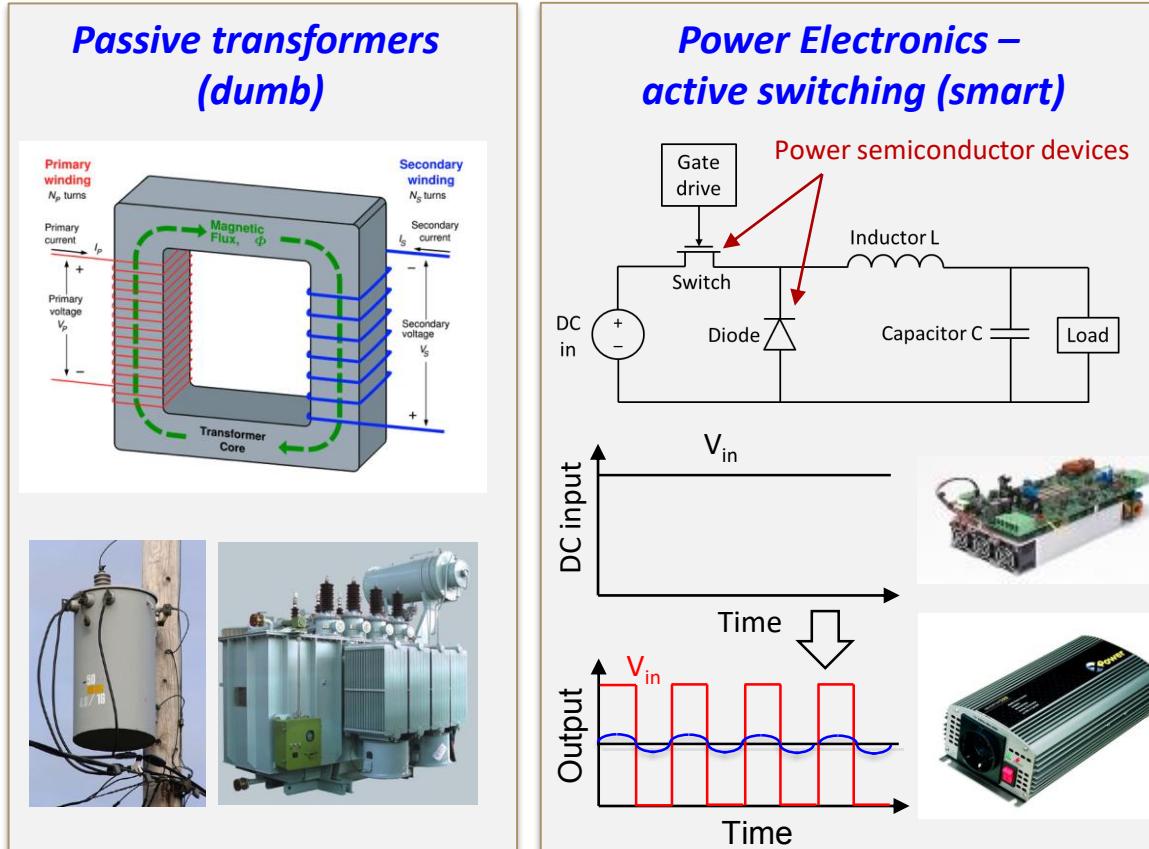
Outline

- **Overview of WBG Power Electronics**
- **Medium-Voltage Vertical GaN Devices**
 - **PN Diodes**
- **Vertical GaN Devices for Electric Vehicles**
 - **JBS Diodes and MOSFETs**

- **Overview of WBG Power Electronics**
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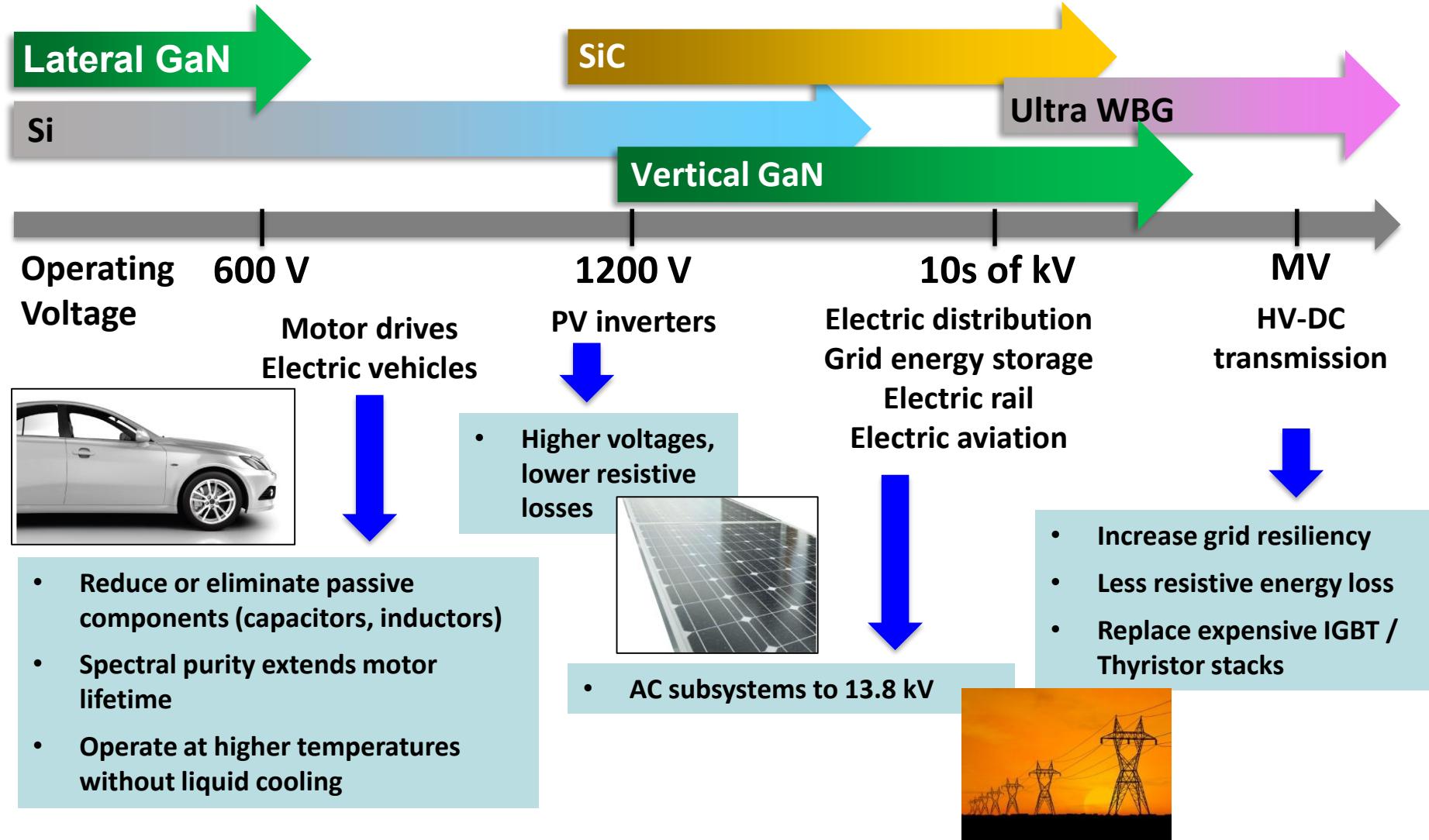
What Are Power Electronics?

Power electronics: Application of solid-state electronics for routing, control, and conversion of electrical power

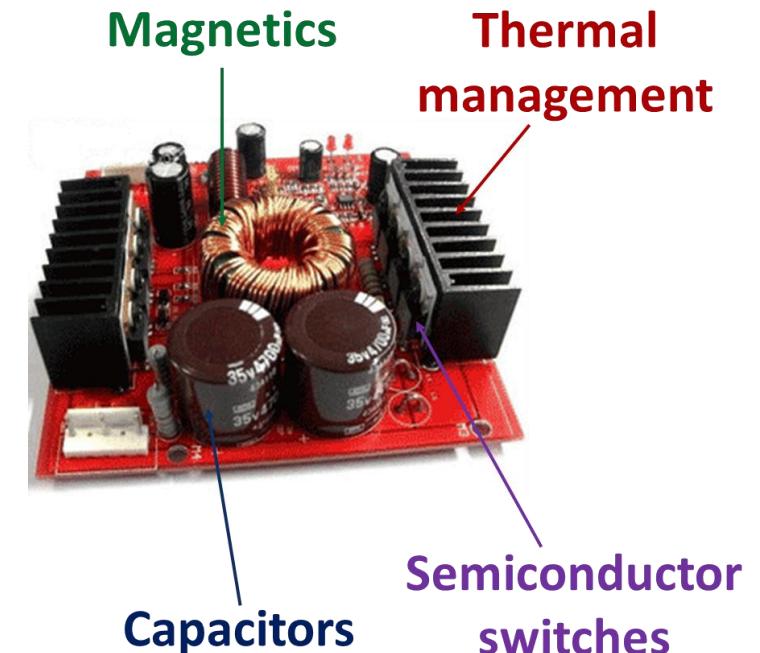
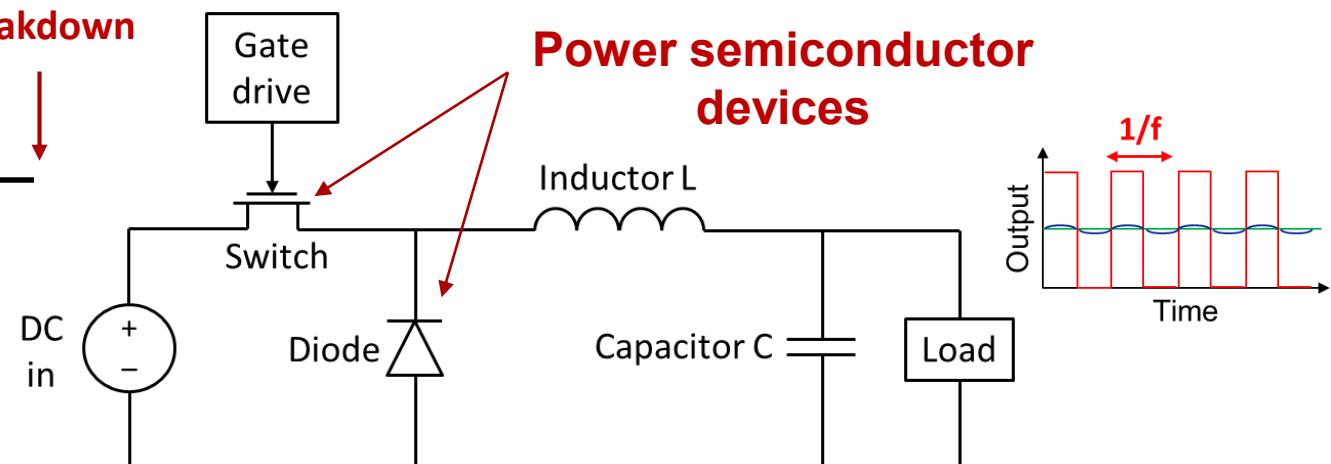
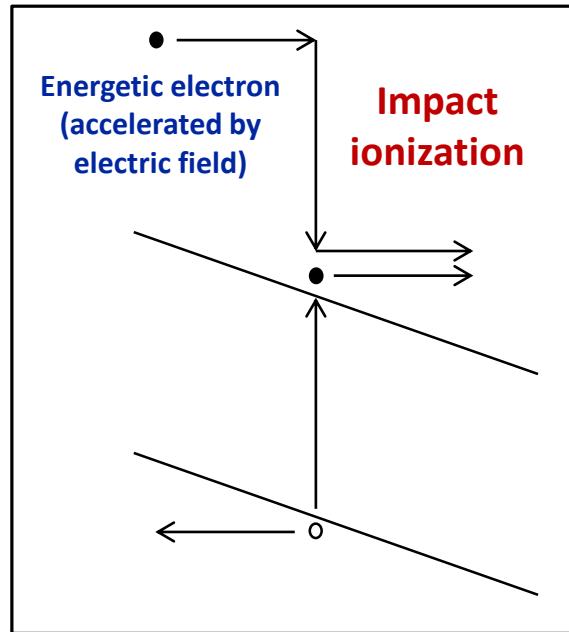
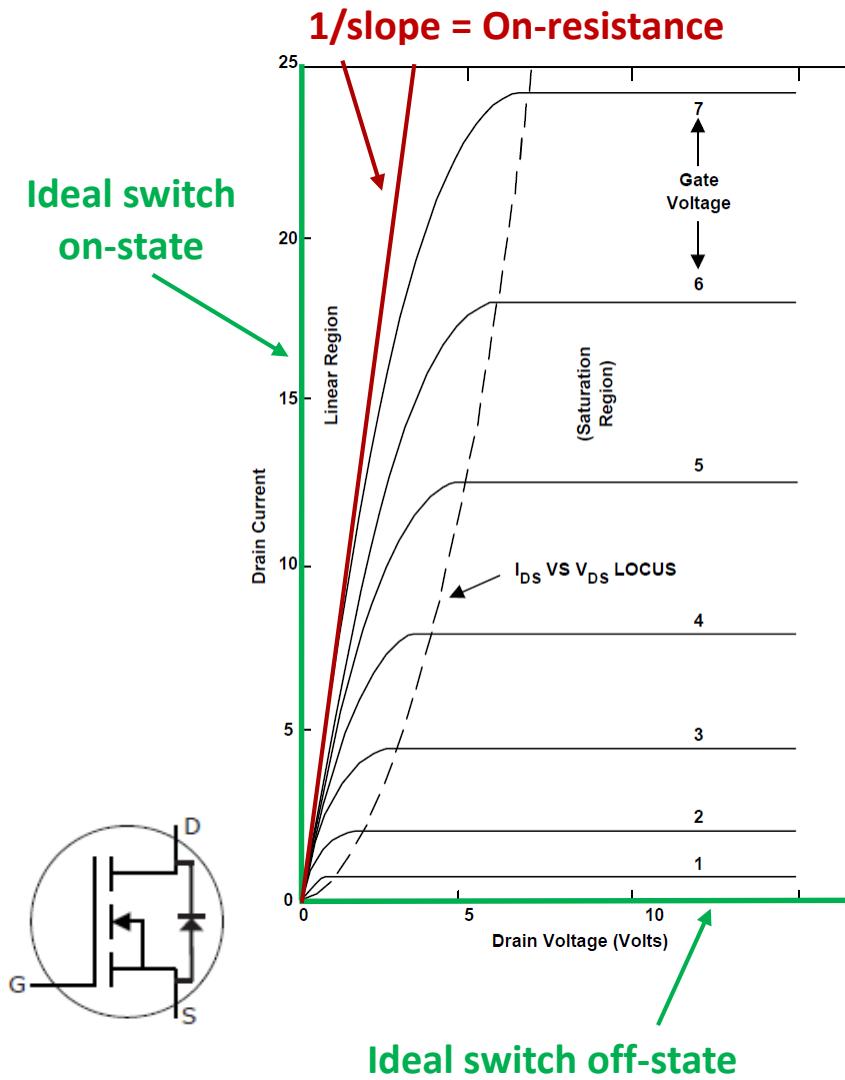


- Current power electronics are limited by the properties of Silicon semiconductor devices
- New system capabilities are enabled by:
 - Higher switching frequency (enables better SWaP)
 - Lower power loss
 - Higher temperature operation
- **Motivation for WBG/UWBG semiconductors**

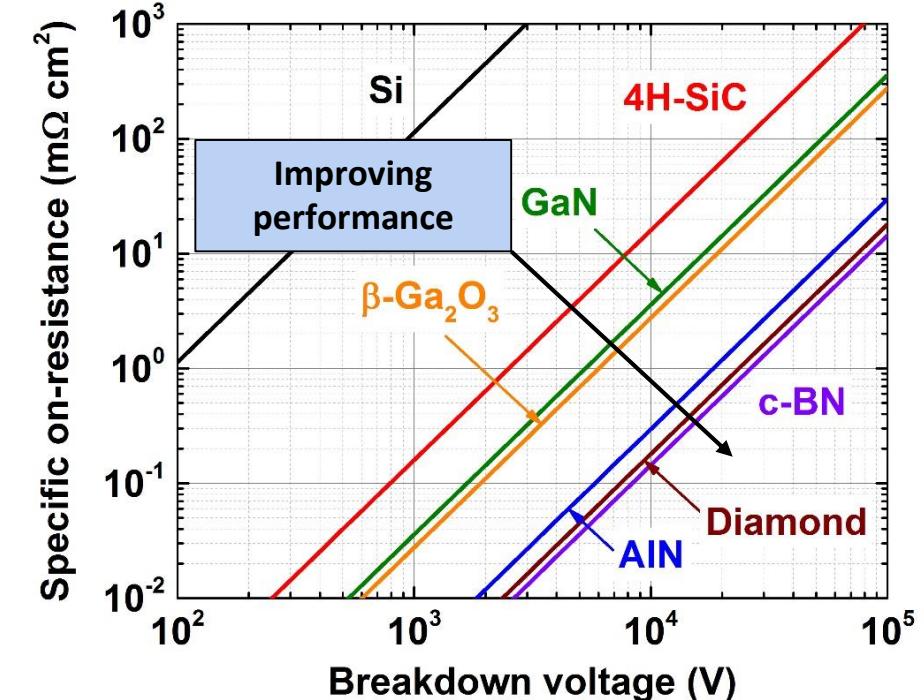
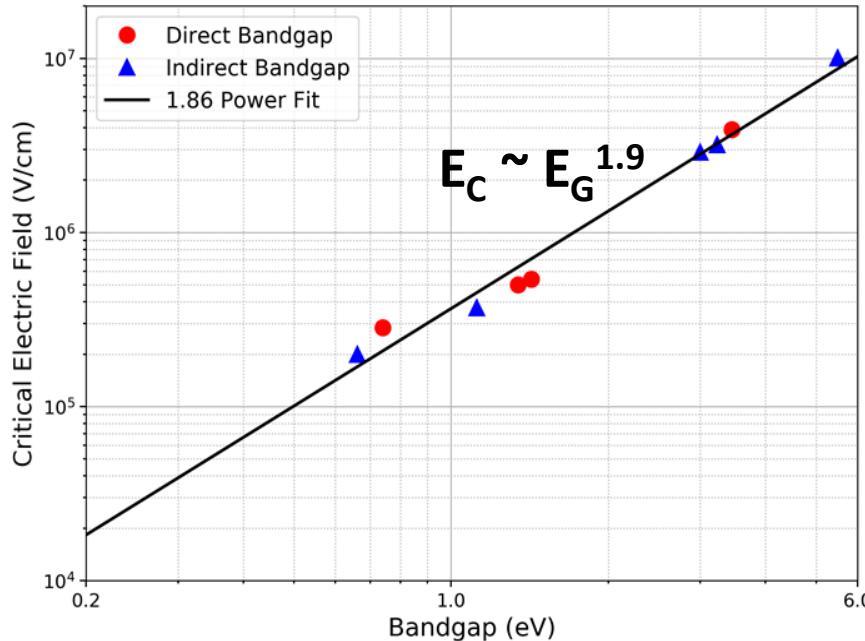
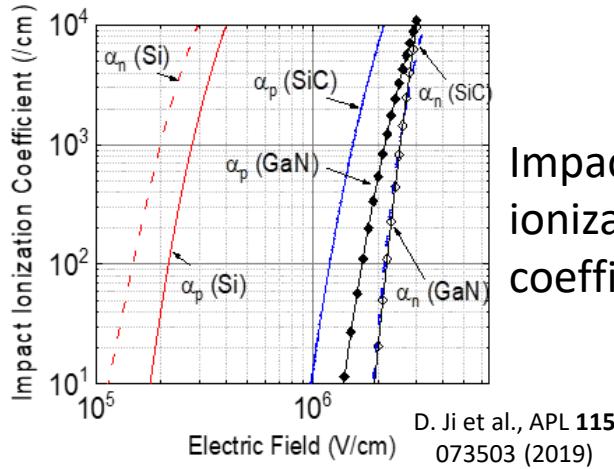
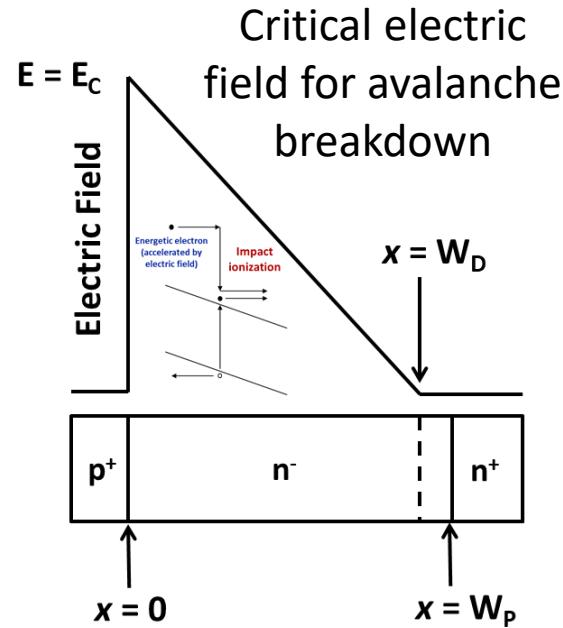
Power Electronics for Energy Efficiency



Power Electronic Devices and Circuits



Advantages of WBG/UWBG Semiconductors



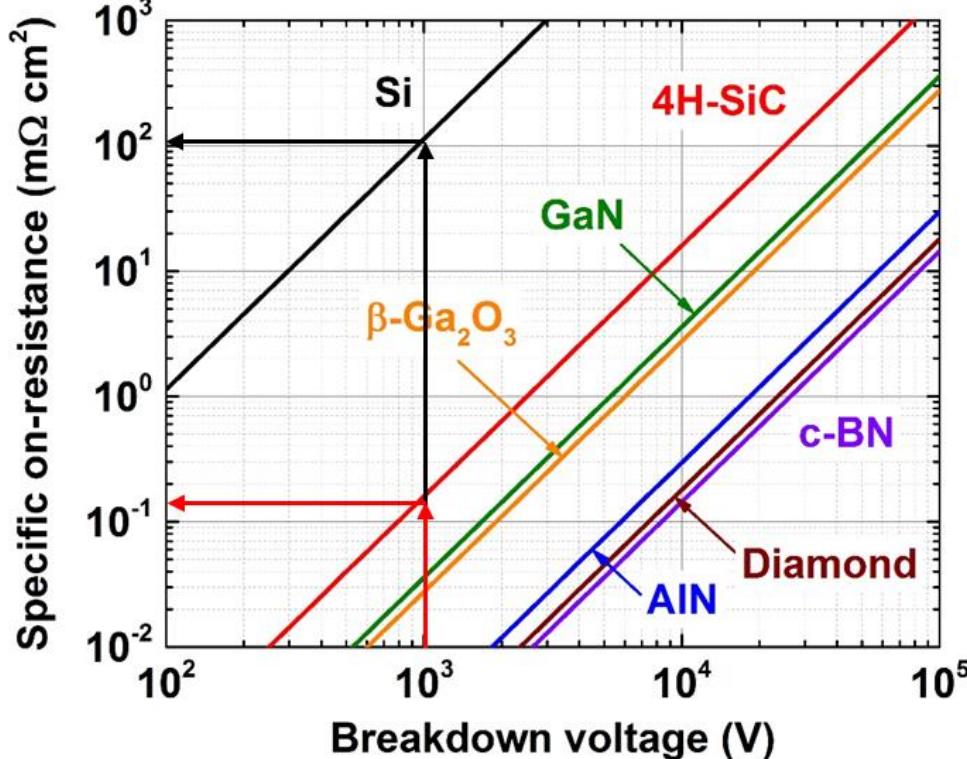
Vertical device:

$$\text{UFOM} = V_B^2 / R_{\text{on,sp}} = \epsilon \mu_n E_C^3 / 4$$

Lateral device:

$$\text{LFOM} = V_B^2 / R_{\text{on,sp}} = q \mu_{\text{ch}} n_s E_C^2$$

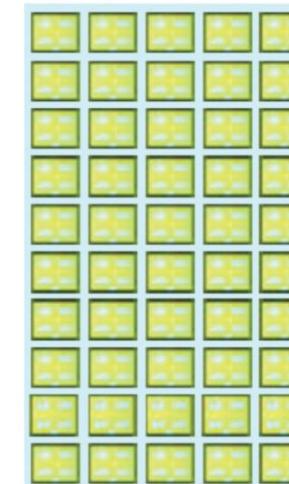
Scaling of WBG/UWBG Power Devices



The scaling that results from the properties of WBG and UWBG materials can be utilized to optimize for switching frequency, conduction loss, and switching loss

- For equivalent breakdown voltage, get lower $R_{on}A$ for (U)WBG device
 - For same R_{on} , (U)WBG device can have *smaller area*
 - Smaller area results in *less capacitance*
 - Gives a *faster switching transient* and *lower loss per switching cycle*

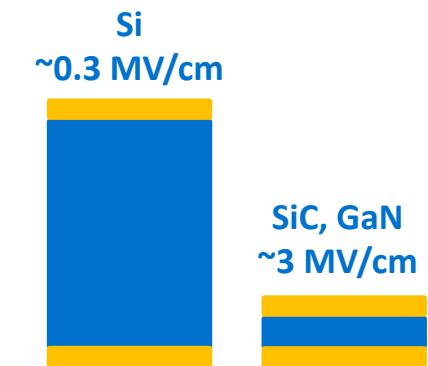
For a given on-resistance (R_{on}) of 10mΩ:



500mΩ, 50 chips
Si-MOSFET

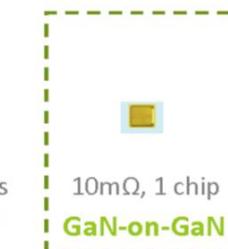


40mΩ, 4 chips
GaN-on-SiC



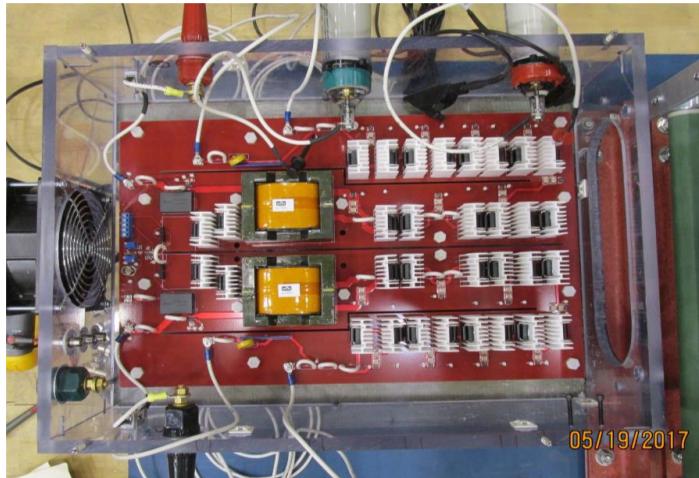
Thinner drift layers required for increasing E_c

GaN-on-GaN lowers die cost while improving $R_{on} \times C_{off}$ switching characteristic



10mΩ, 1 chip
GaN-on-GaN

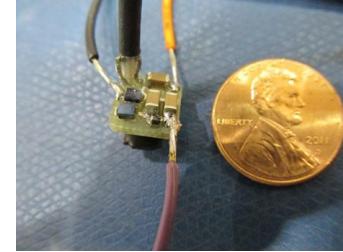
Improvements in Converter Power Density



SNL SiC hybrid switched-capacitor boost converter (ARPA-E)

- First prototype: 0.5 kV → 10.1 kV (gain = 16.8) at 2.6 kW, 95.3% efficient, 410 in³
- Second prototype: +2% efficiency, 55% volume

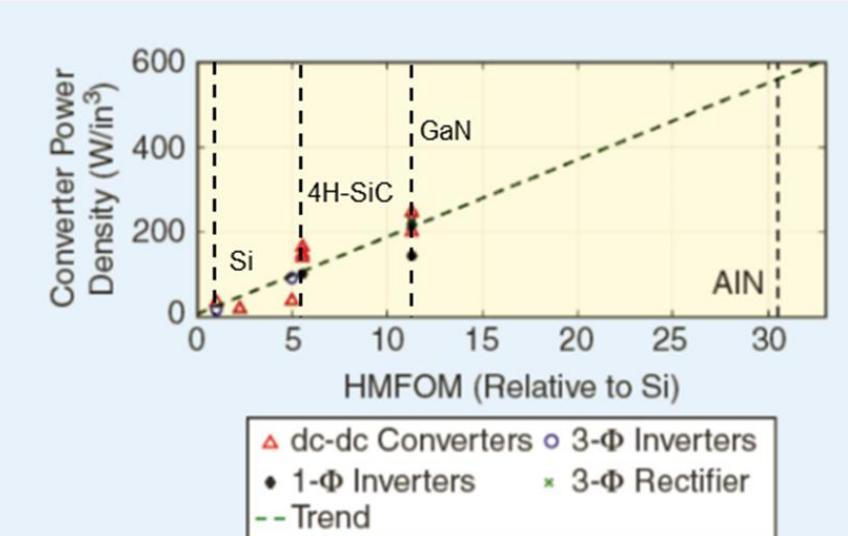
Over an order of magnitude improvement in power density is enabled by WBG and UWBG semiconductors compared to Si



SNL GaN HEMT "Coin Converter"
90 V, 90 mA → 215 W/in³



SOA commercial microinverter
250 W in 59 in³ → 4.2 W/in³



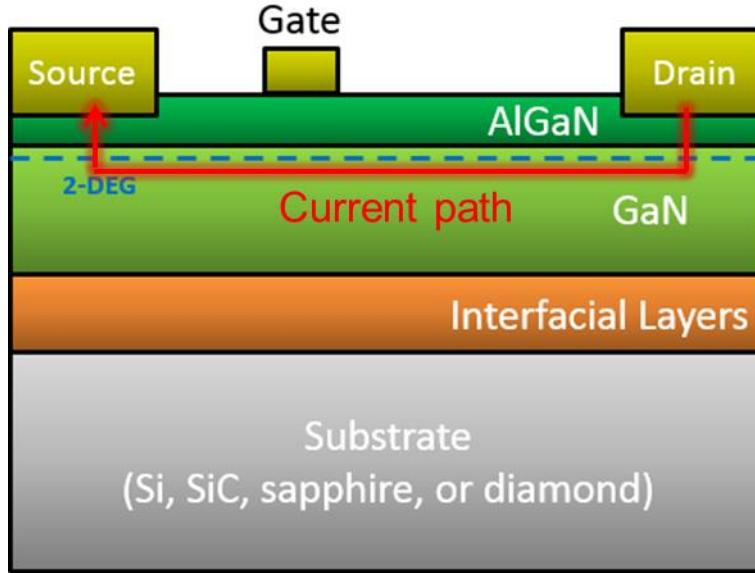
R. J. Kaplar, J. C. Neely, et al., *IEEE Power Electronics Magazine* (March 2017)

Relative Figures of Merit:

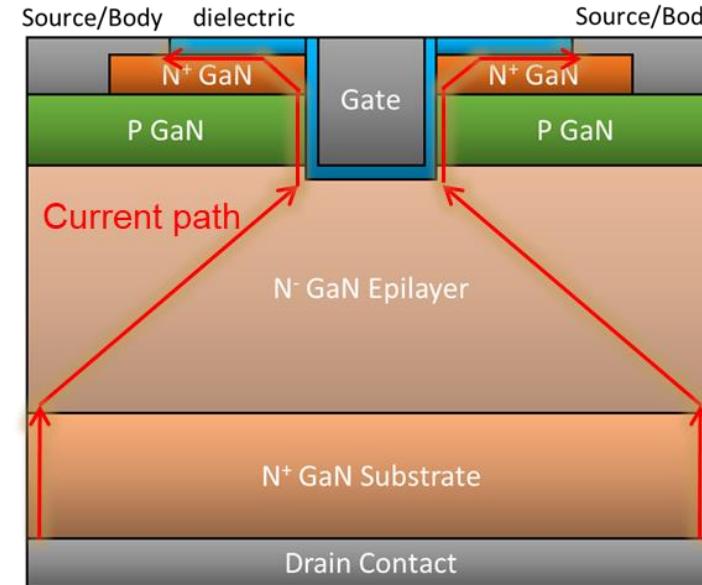
- Vertical UFOM = $\varepsilon \mu_n E_c^3$
- Lateral LFOM = $q \mu_{ch} n_s E_c^2$
- Huang Material FOM = $E_c \mu_n^{1/2}$
- HM-FOM seems to be a good predictor of power density in a variety of power converter types*

Lateral vs. Vertical GaN Power Devices

**Lateral Current Flow
(HEMT)**



**Vertical Current Flow
(Trench MOSFET)**



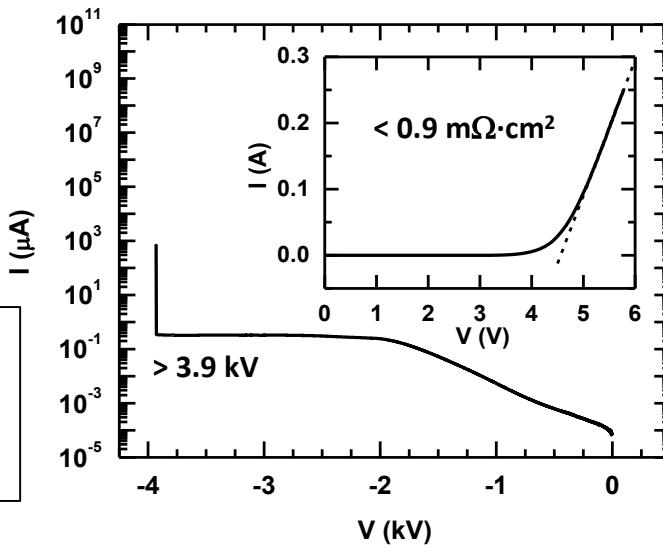
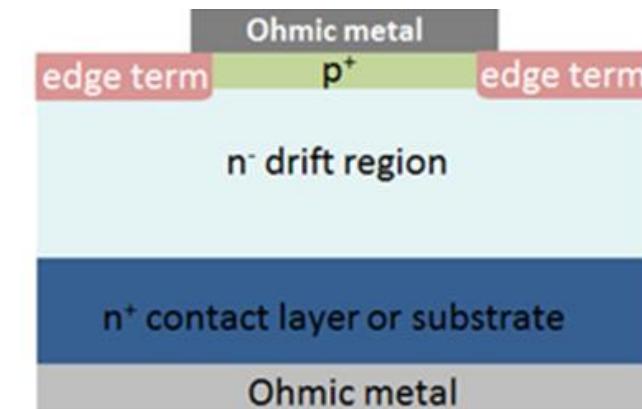
- Polarization-doped heterostructure
- High electron mobility in 2DEG for low R_{ON}
- High-frequency operation (up to ~ 1 MHz)
- Low blocking voltage ($< \sim 650$ V, scales with area)
- Typically grown on foreign substrate
- Commercially available

- Selective-area impurity doping required
- Mobility limited by channel
- Capable of large blocking voltages (> 1200 V, not dependent on area)
- Grown on native GaN substrates

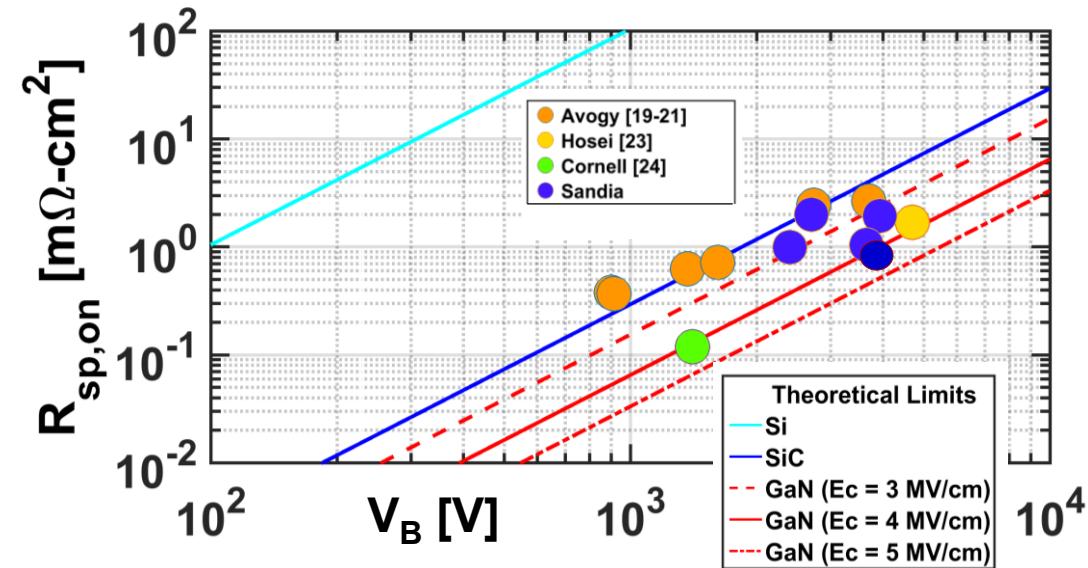
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Overview of Vertical GaN Technology

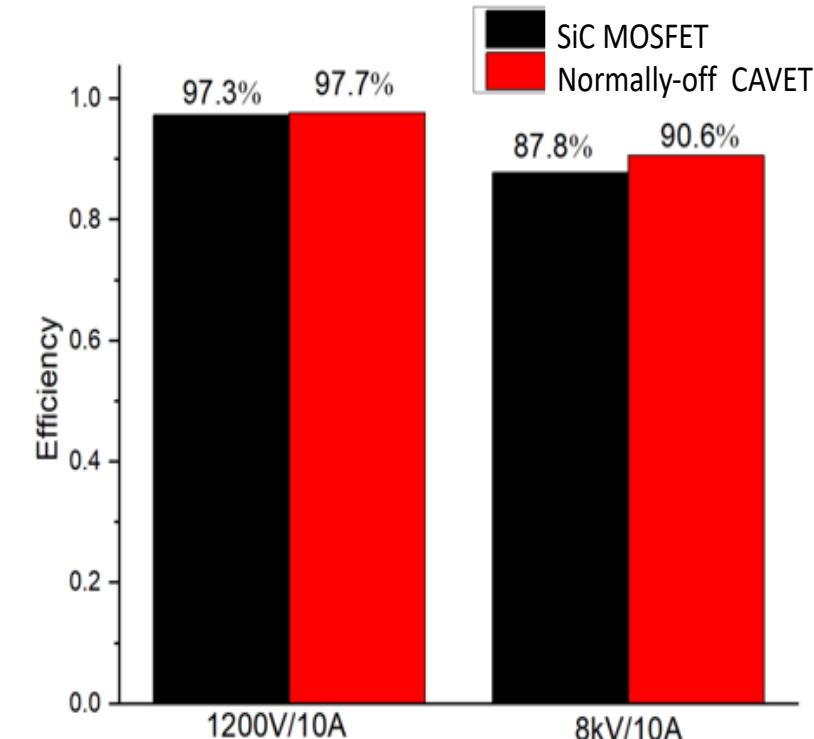


- Need to extend the limits of vertical GaN power device technology for medium-voltage applications (~1.2-20 kV)
 - Need to increase V_B by 4x from today's SOA
 - Challenges: Thick drift region, low net doping, edge termination
- Need to establish a domestic foundry process for vertical GaN power devices



Vertical GaN Advantages for MV Power Electronics

- Critical field of GaN ~ 2.8 MV/cm at $N_D = 1 \times 10^{16}$ cm $^{-3}$ and room temperature based on most recent impact ionization measurements [1]
- Slightly higher than E_C of SiC at the same temperature and doping [2]
- But higher mobility of GaN ~ 1200 cm 2 /Vs [3] compared to ~ 950 cm 2 /Vs for SiC [2] at the same doping and temperature lead to improvements in power converter efficiency [4], ***particularly for medium-voltage devices (> 1.2 kV)***
- But devices are not widely available – ***a vertical GaN foundry is needed that monitors yield, reliability, etc.***



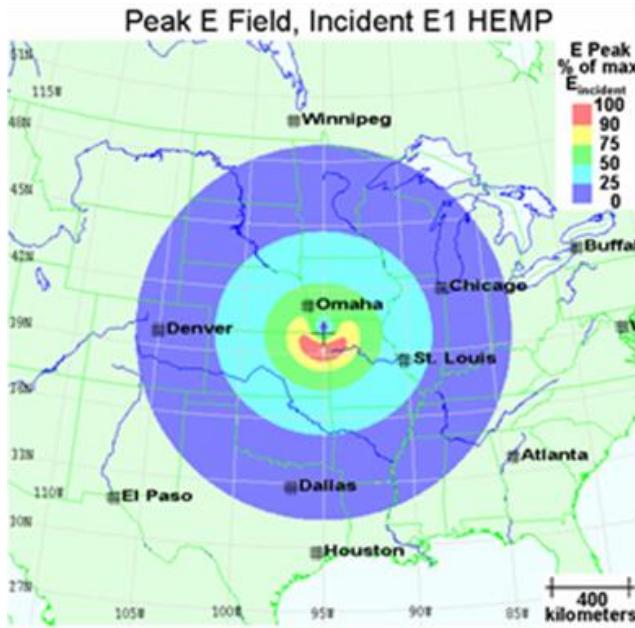
[1] D. Ji, B. Ercan, and S. Chowdhury, "Experimental Determination of Impact Ionization Coefficients of Electrons and Holes in Gallium Nitride Using Homojunction Structures," *Appl. Phys. Lett.* **115**, 073503 (2019).

[2] J. A. Cooper and D. Morissette, "Performance Limits of Vertical Unipolar Power Devices in GaN and 4H-SiC," *Elec. Dev. Lett.* **41**, 892 (2020).

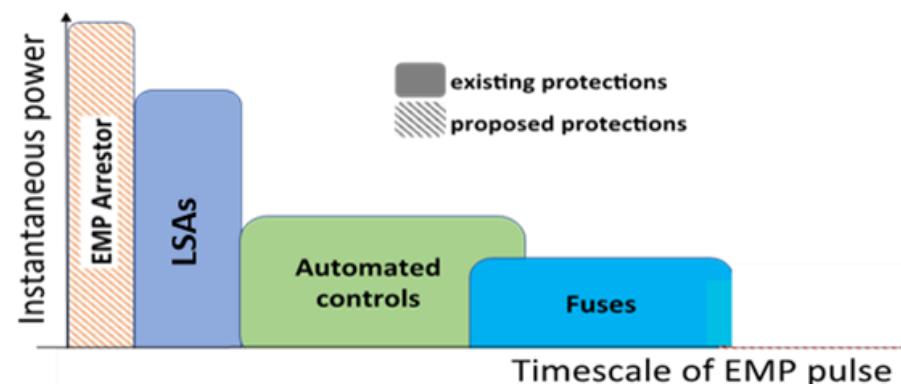
[3] I. C. Kizilyalli, A. P. Edwards, O. Aktas, T. Prunty, and D. Bour, "Vertical Power PN Diodes Based on Bulk GaN," *IEEE Trans. Elec. Dev.* **62**(2), 414 (2015).

[4] D. Ji and S. Chowdhury, "On the Progress Made in GaN Vertical Device Technology – Special Issue on Wide Band Gap Semiconductor Electronics and Devices," *Int. J. High-Speed Elec. Sys.* **28**(01n02), 1940010 (2019).

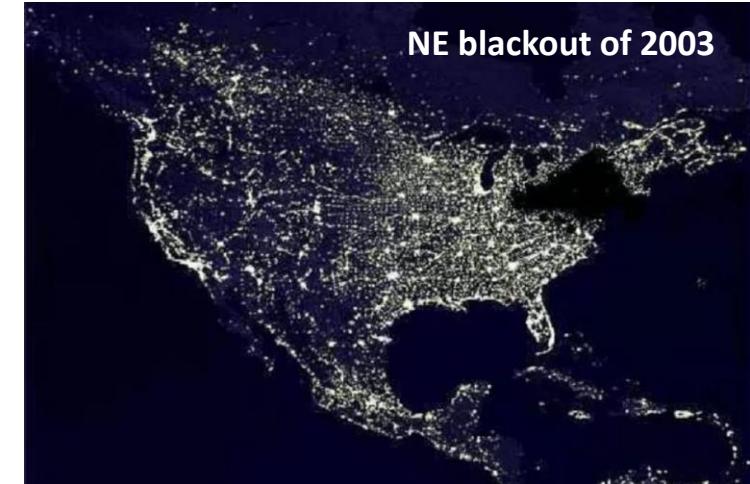
Fast Protection for the Electric Grid



- Electromagnetic pulses are a threat to the grid
 - Very fast E1 component ($< 1 \mu\text{s}$)
 - Unaddressed by current SoA technology (LSAs)



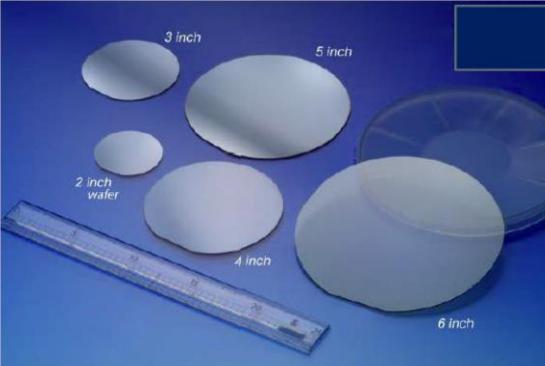
- Transient protection is needed for MV grid-connected systems

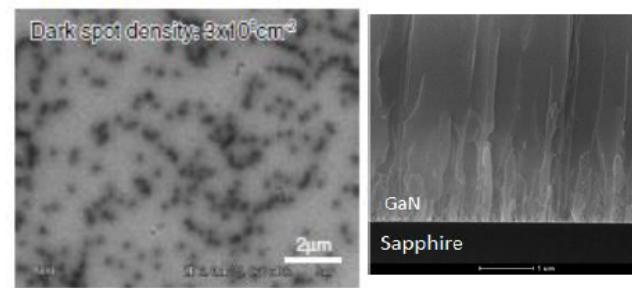


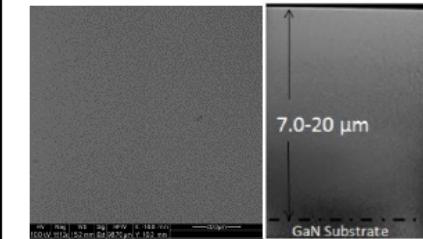
J. S. Foster Jr. et al., "Report of the Commission to Assess the Threat to the United States from Electromagnetic Pulse (EMP) Attack: Critical National Infrastructures," *Defense Technical Information Center* (2008).

Native Substrates for Vertical GaN Devices

Attributes	GaN on Si	GaN on SiC	GaN on Bulk-GaN
Defect Density (cm⁻²)	10^9	5×10^8	10^3 to 10^6
Lattice Mismatch, %	17	3.5	0
CTE Mismatch, %	54	25	0
Layer Thickness (μm)	< 5	< 10	> 50
Breakdown Voltage (V)	< 1000	< 2000	> 5000
OFF State Leakage	High	High	Low
Device Types	Lateral	Lateral	Vertical and Lateral



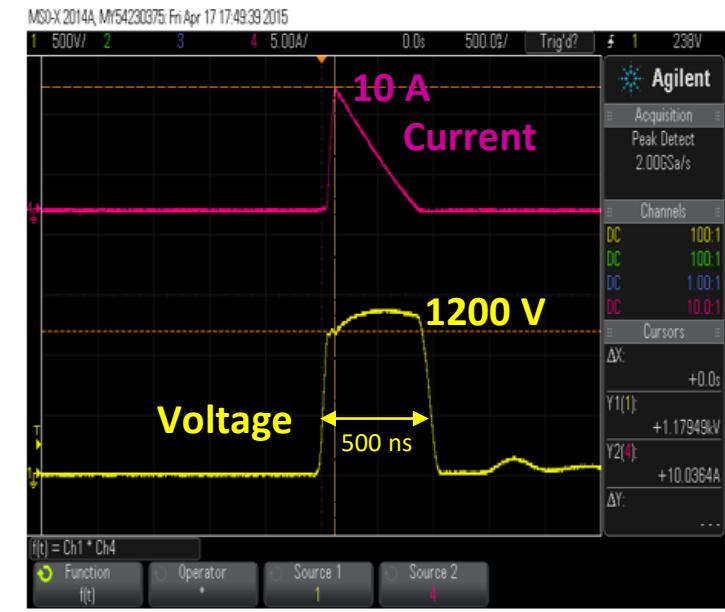
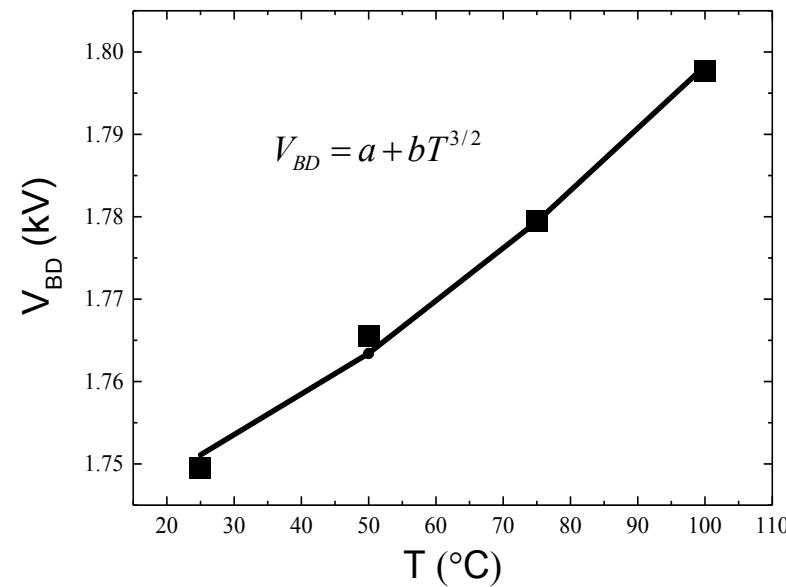
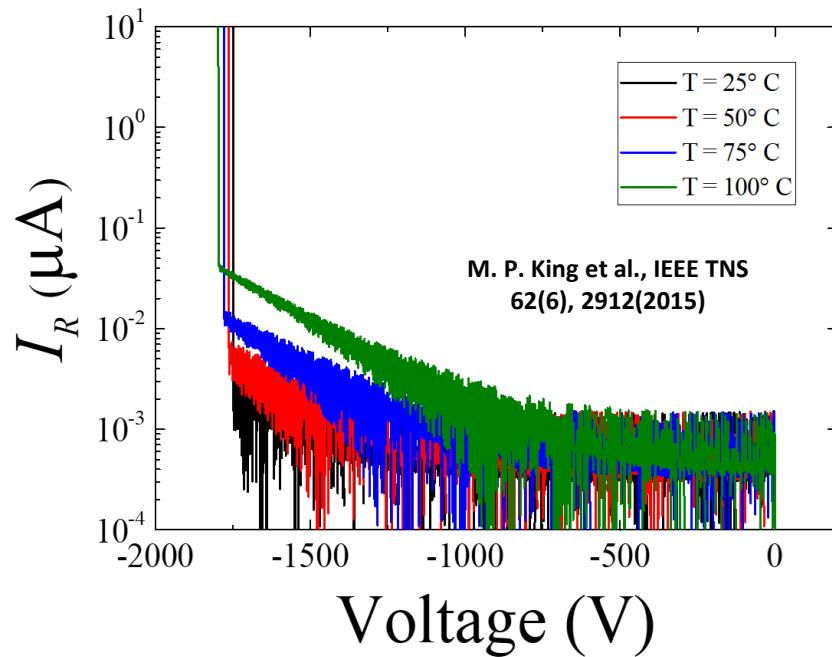




Avalanche Ruggedness of Vertical GaN



- Avalanche breakdown mechanism demonstrated via temperature dependence
- Avalanche ruggedness demonstrated in real power switching circuits
- *Very different from the situation for GaN-on-Si power devices, where avalanche breakdown does not occur*

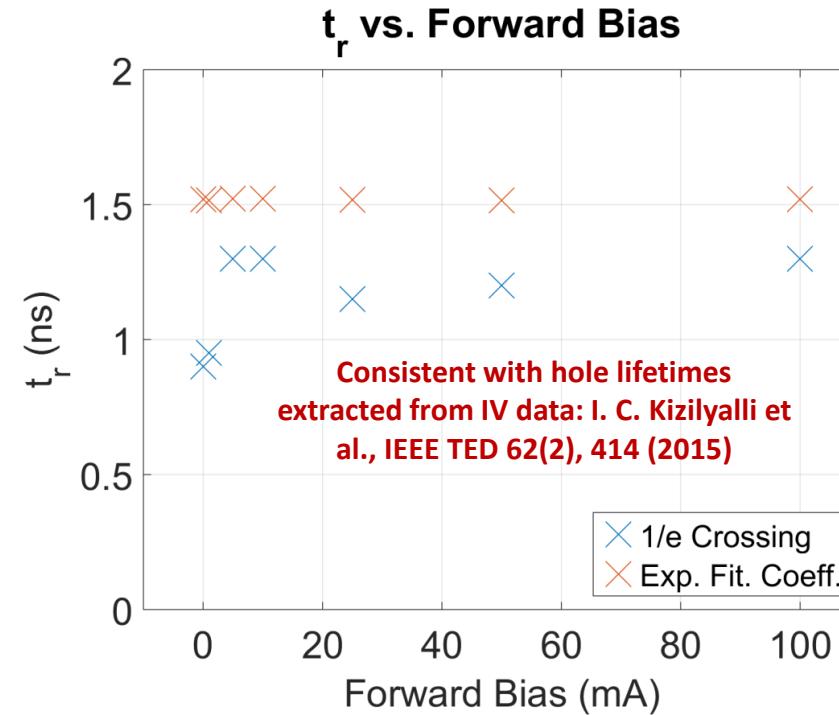
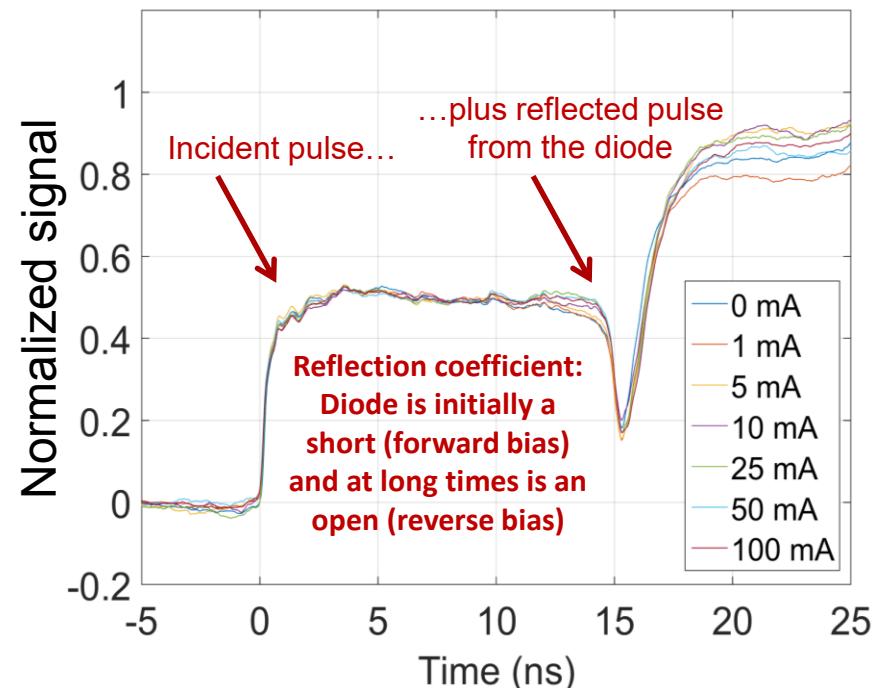


O. Aktas and I. C. Kizilyalli, IEEE EDL 36(9), 890 (2015)

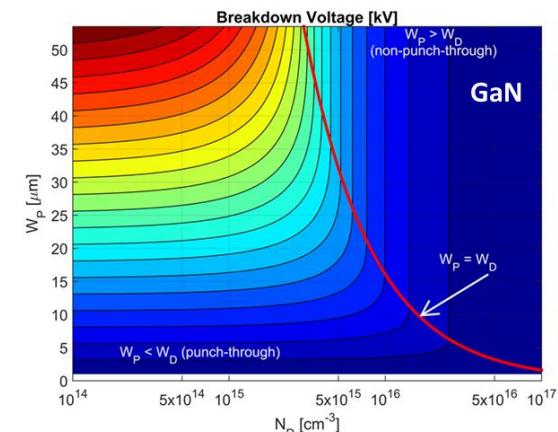
Carrier Transport in Vertical GaN

Reverse recovery measurements on vertical GaN diodes to determine carrier lifetime

- 100 V reversing pulses used with various forward currents
- Reverse-recovery time is invariant to forward bias, implying t_r is limited by capacitance
- Measured times provide an upper limit for hole lifetime – $\tau_h \approx 2$ ns



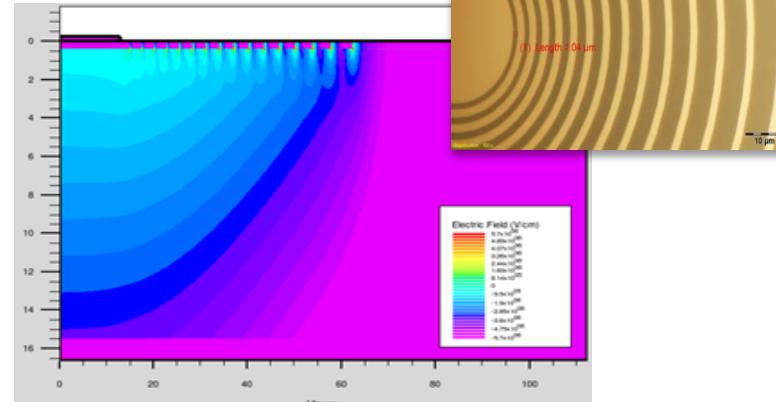
Ideal planar limit of GaN breakdown depends on drift layer thickness and doping:



But premature breakdown will occur at the device surface, edge, etc. unless mitigations are taken to prevent this – edge termination

Guard Rings

J. Dickerson et al., EMC (2016)



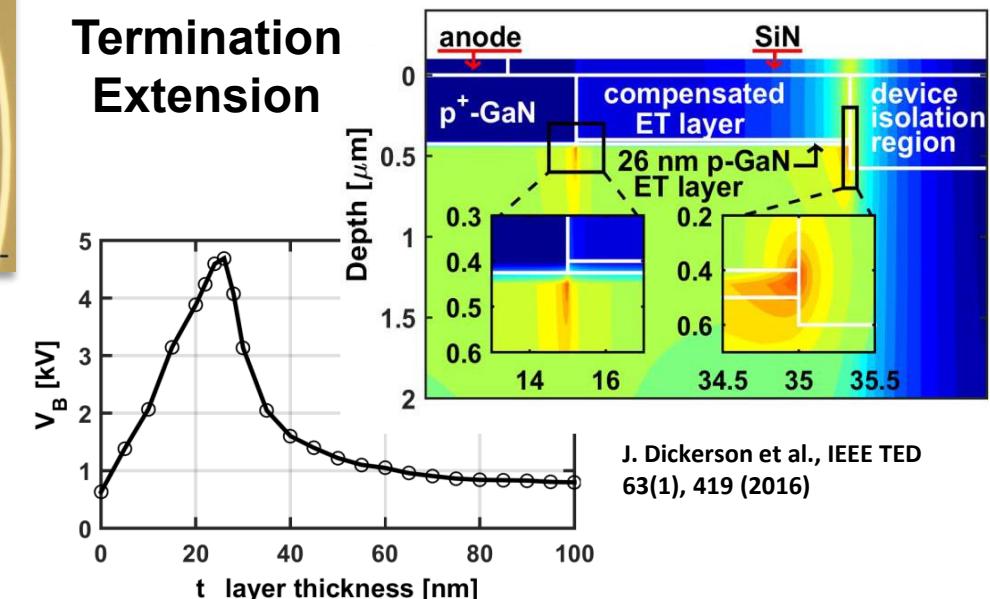
The diagram illustrates a diode structure with an anode at the top and a cathode at the bottom. The anode is labeled P^+ and the cathode is labeled N^- . A hatched region represents the p-n junction. The electric field is shown as a downward-pointing arrow labeled W_p on the anode side and an upward-pointing arrow labeled W_N on the cathode side. The angle between the electric field and the normal to the junction is labeled θ . The surface width of the depletion region is labeled $W_{surface}$. The depletion region is shaded with diagonal lines. The cathode is labeled $Cathode$ at the bottom.

if $\theta \downarrow \Rightarrow W_{surface}/W_N \uparrow \Rightarrow \epsilon_{surface} \downarrow \Rightarrow V_{BR} \uparrow$

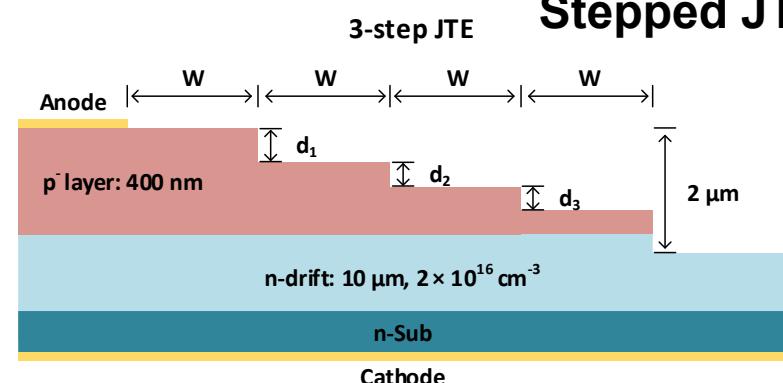
A. Binder et al., WiPPDA (2019)

Various approaches to edge termination

Junction Termination Extension

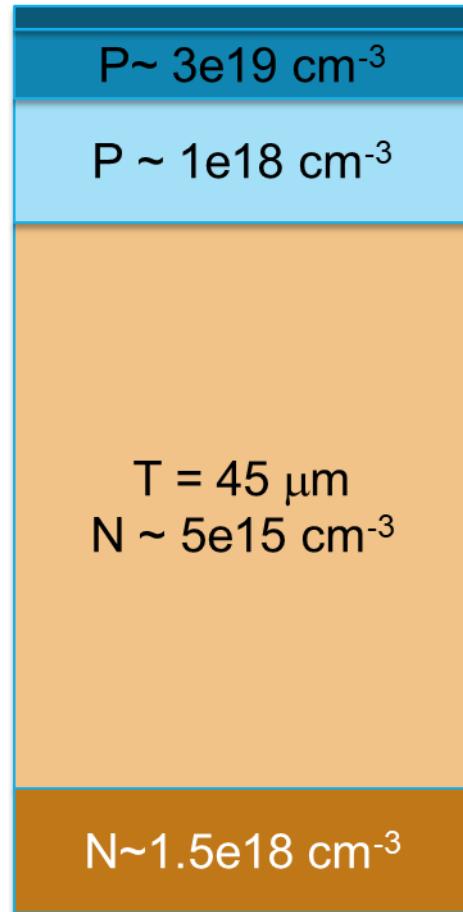


Stepped JTE



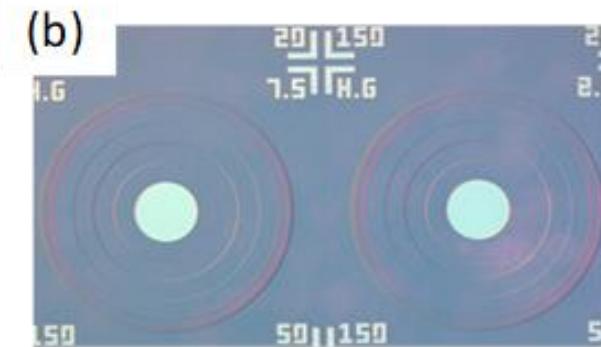
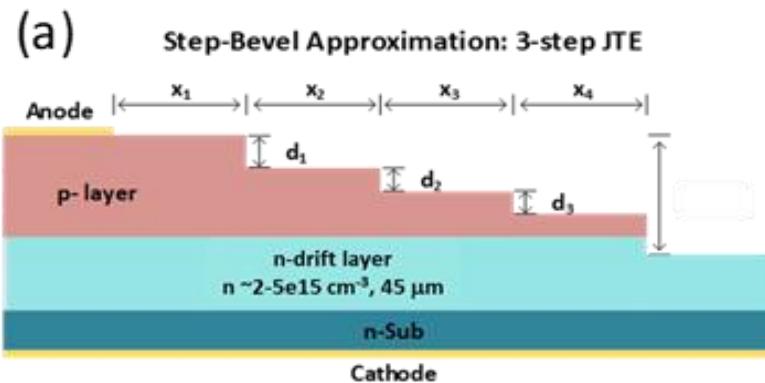
K. Zeng

Fabrication of PN Diodes with Thick Drift Regions

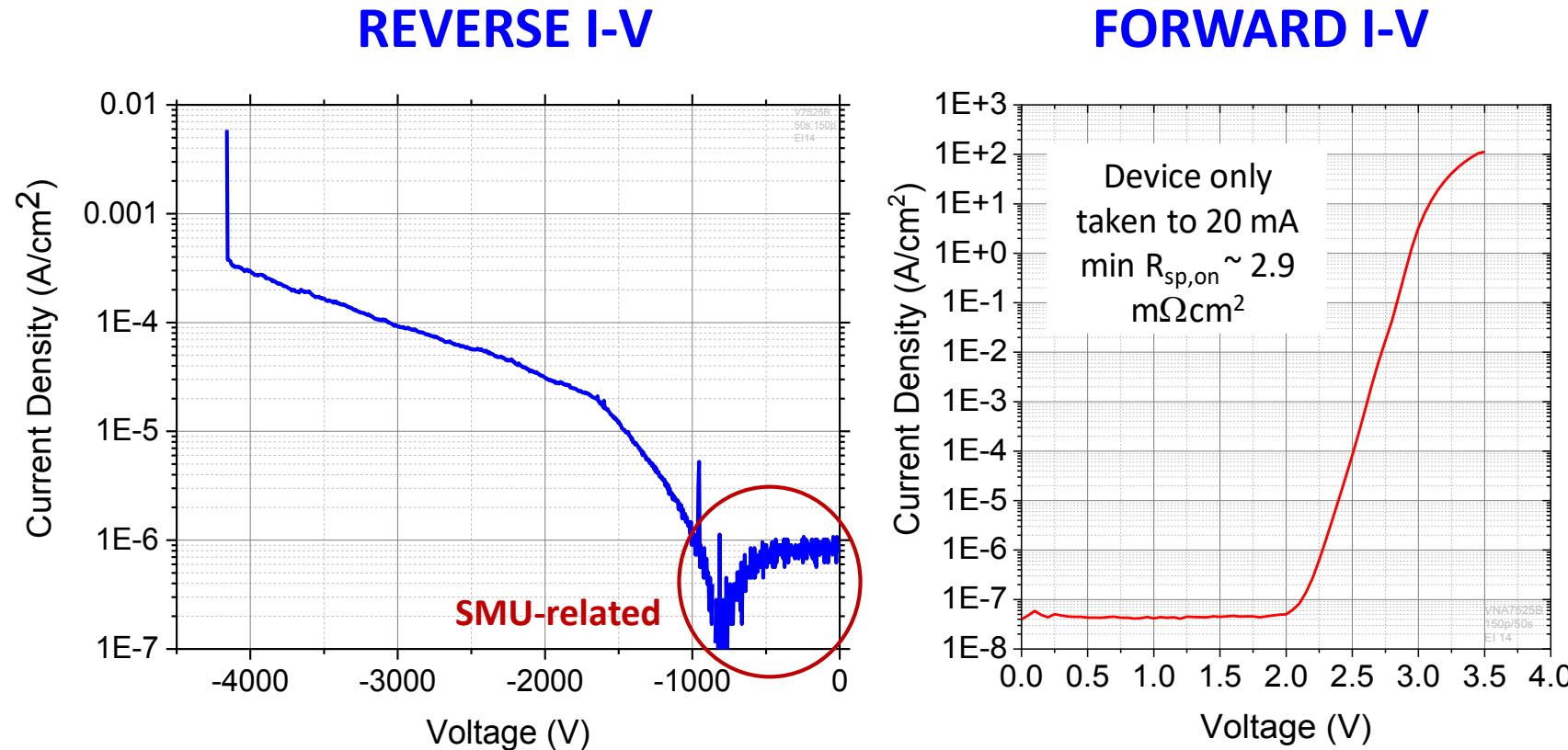


C-V mapping confirmed highest reverse breakdown voltage devices from regions of wafer with drift region carrier density $\sim 2.2\text{-}3.0 \times 10^{15} \text{ cm}^{-3}$

Edge termination: Multi-step ICP-etched JTE

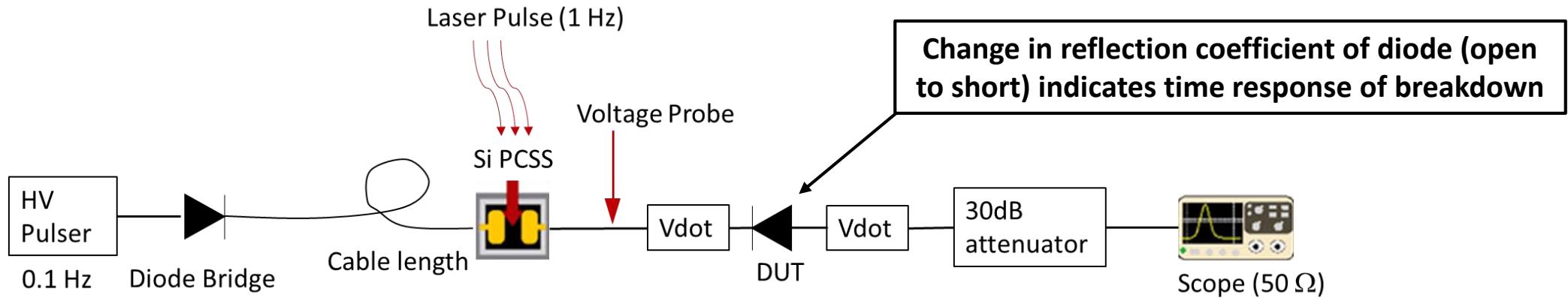


Performance of Medium-Voltage GaN Diodes

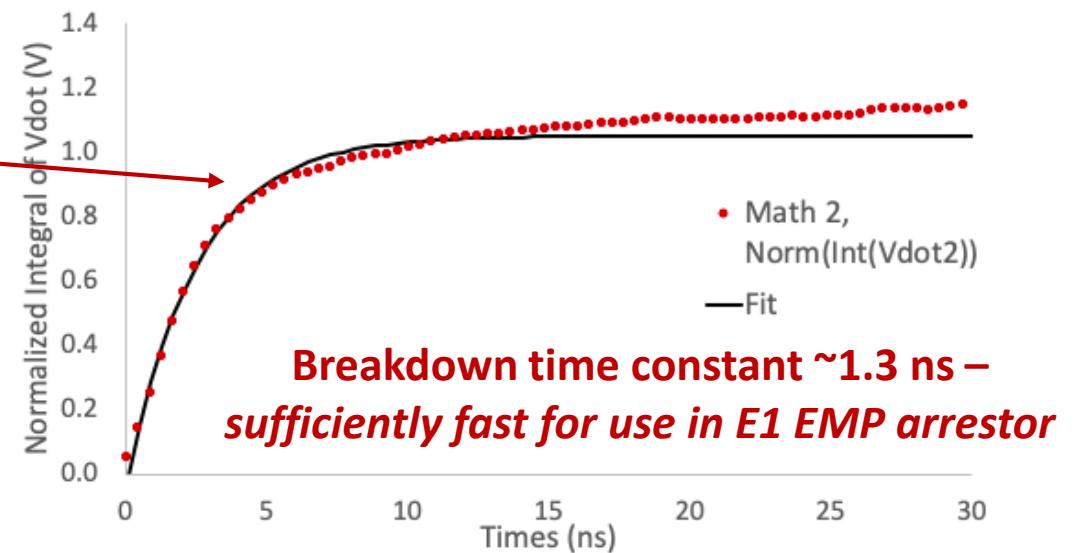
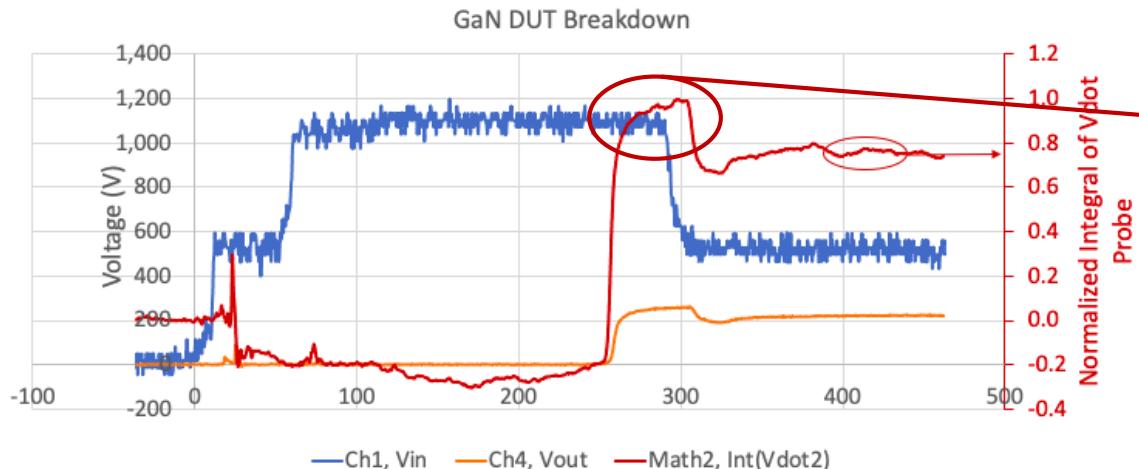


- Best devices > 4 kV; estimate $\sim 70\%$ V_B of ideal planar diode
- Less than 1 mA/cm 2 leakage @ 80% V_B target

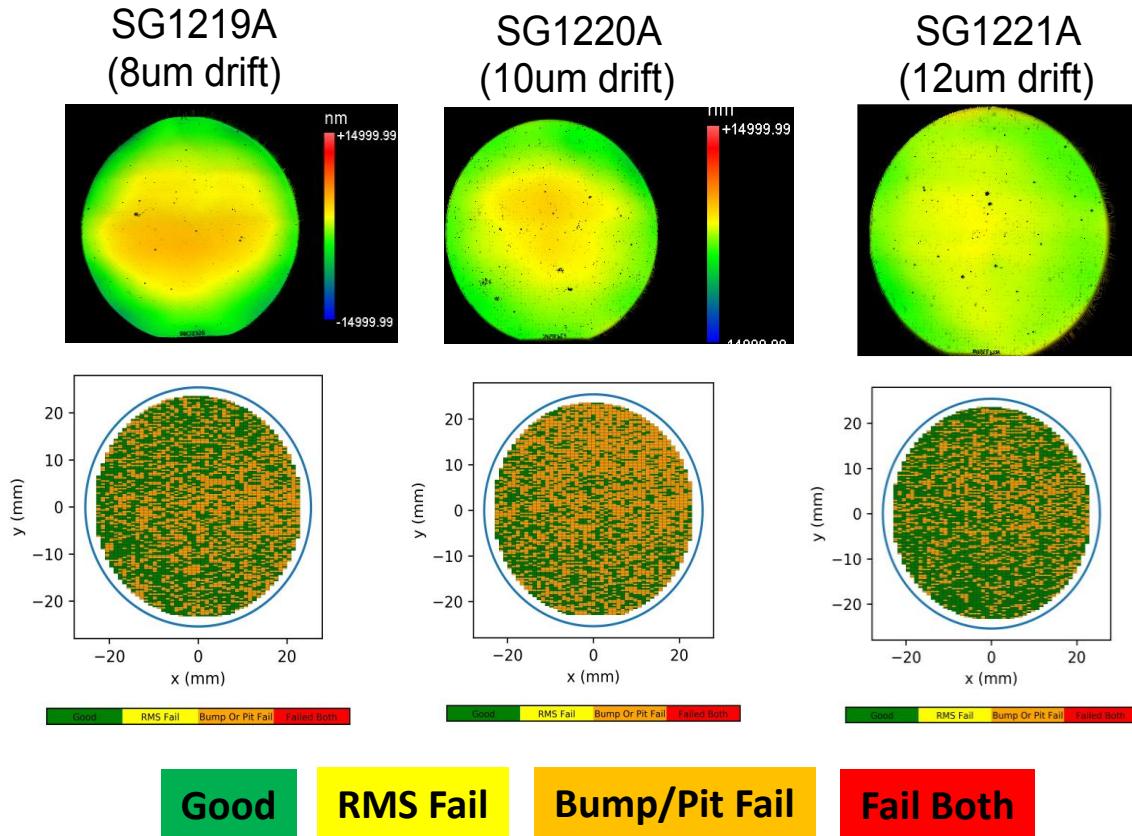
Time Response of GaN Avalanche Breakdown



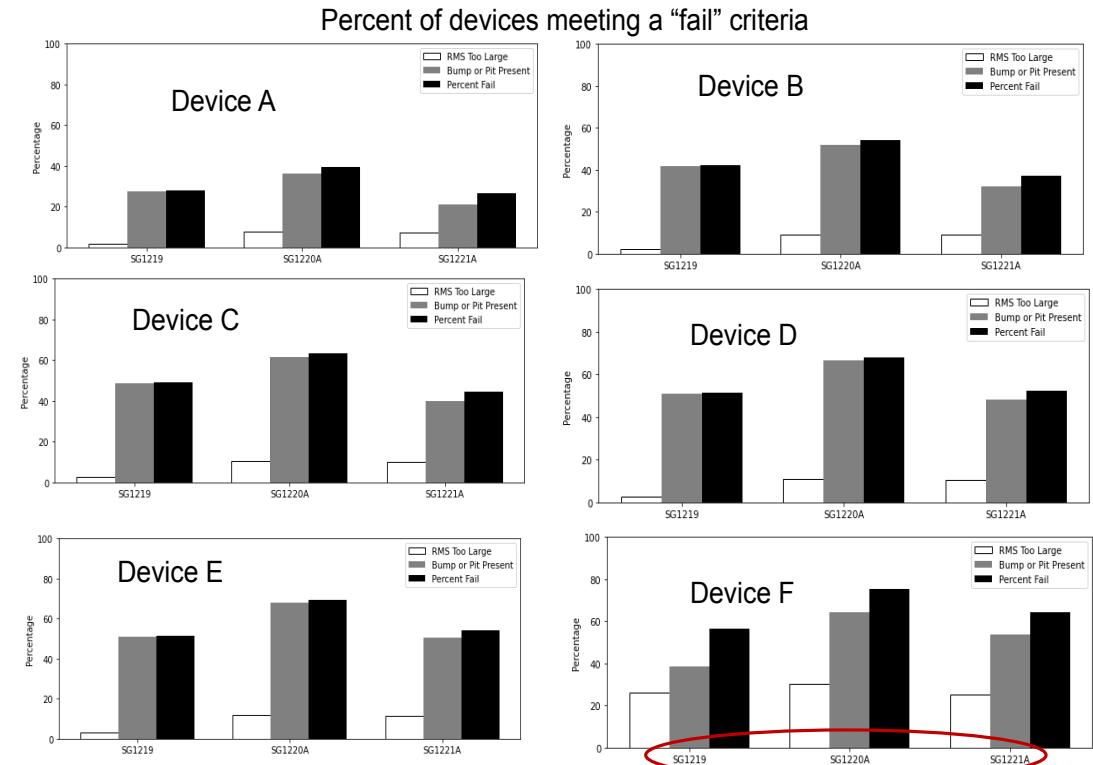
Tested 1.2 kV vertical GaN diode



Vertical GaN Foundry Wafer Metrology

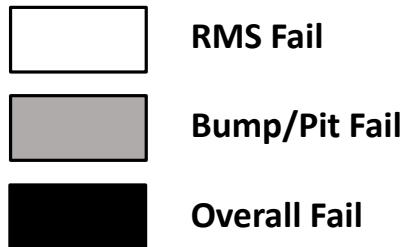


- Evaluate yield based on particles/pits and RMS roughness
- No clear trend in RMS roughness with drift layer thickness
- Evaluating yield for device geometries A-F



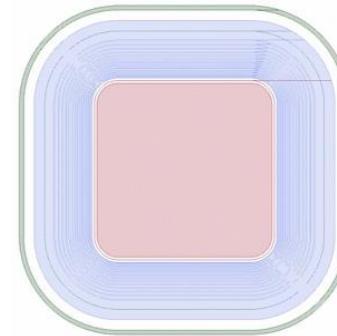
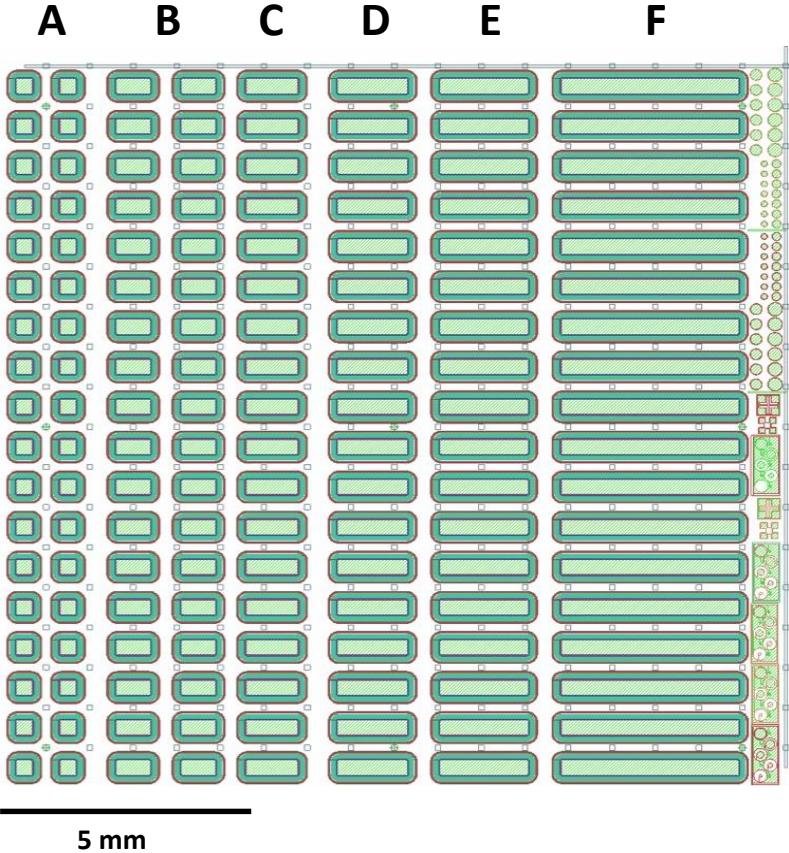
Geometry	Area (mm ²)	Devices (per 2" wafer)
A	0.105	280
B	0.215	280
C	0.325	150
D	0.430	150
E	0.535	150
F	1.05	140
Total		1150

Three wafers



T. Anderson, NRL

Foundry Mask Layout



Base cell:
 $0.35 \times 0.35 \text{ mm}^2$ anode

Larger devices scaled
only in x-direction to
avoid crossing dot-
cores (for now)

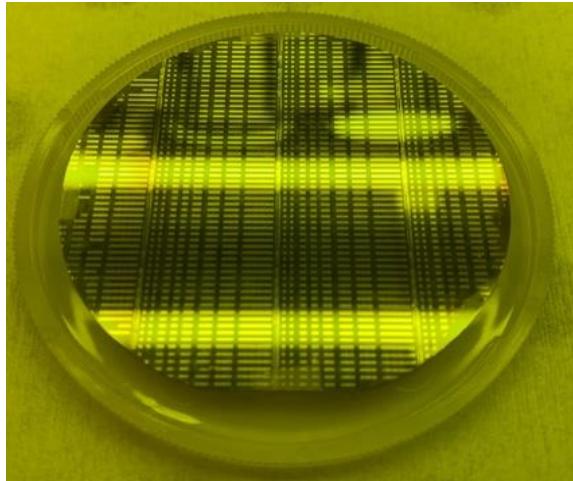
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Features:

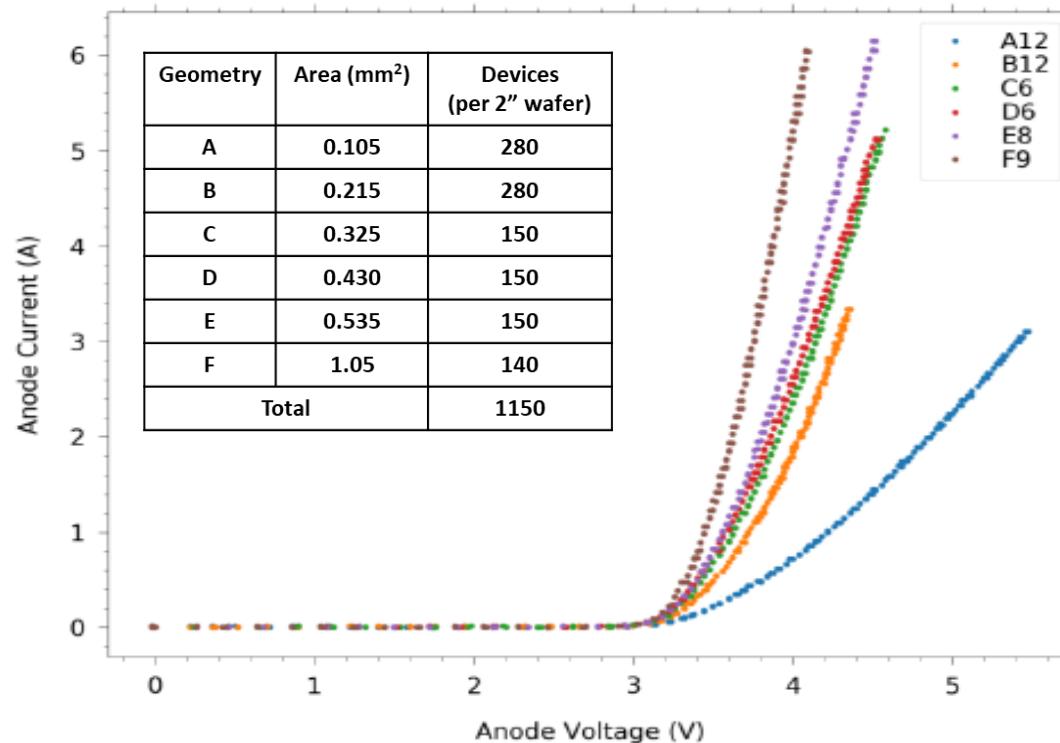
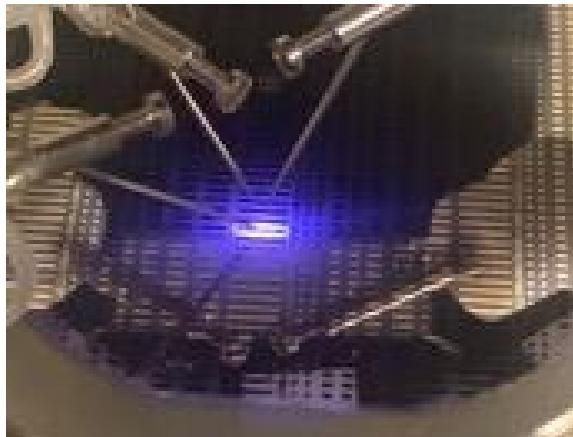
- Global alignment
- P-GaN ohmic CTLM
- P-GaN Hall
- Isolation test
- Termination test
- Small diameter circular diodes
- JTE and GR termination designs
- Passivation / overlay for packaging

Foundry Electrical Testing

Typical
foundry
wafer

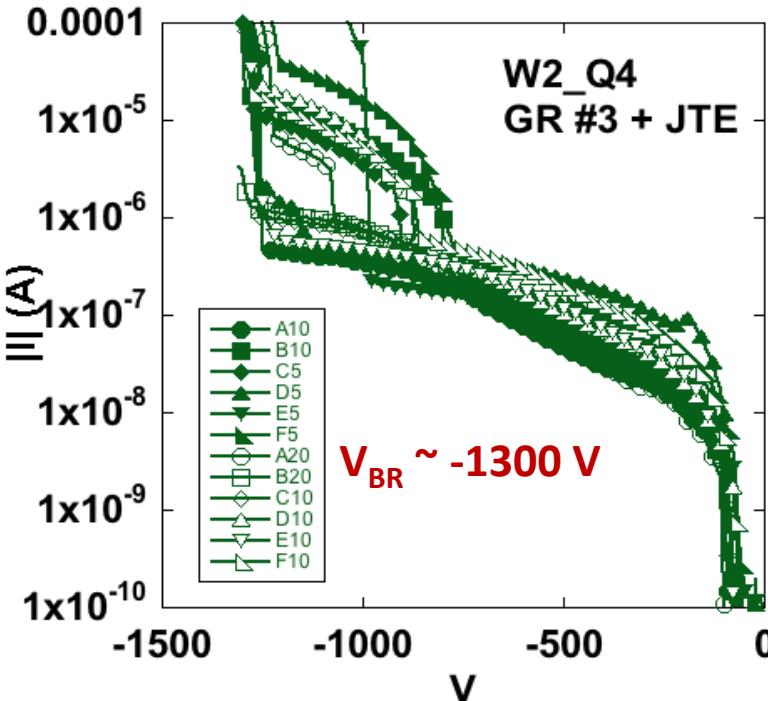


Wafer
under
test



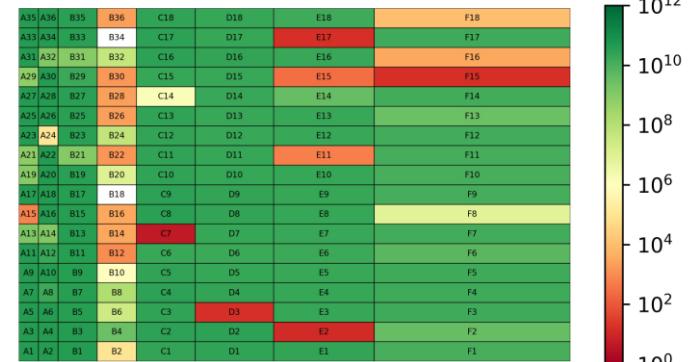
- Representative forward I-V curves for device types A-F
 - Largest devices achieve ~6 A forward current

Foundry Yield Analysis

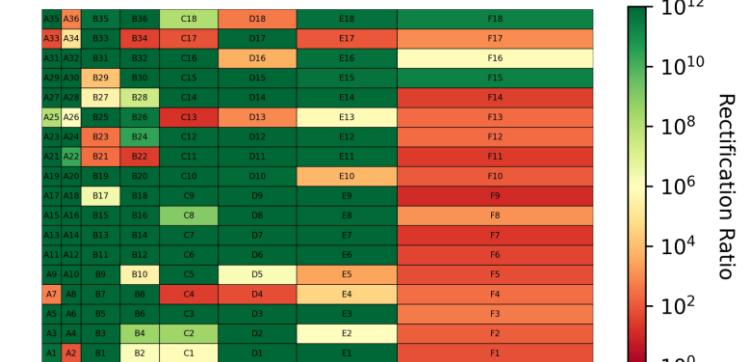


- Multiple devices achieve breakdown >1.3 kV, which is $\sim 90\%$ of the parallel-plane value

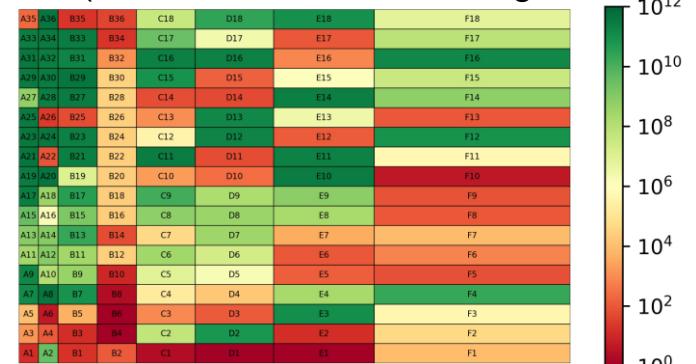
NL2-W1 (base structure, aligned to dot-core)



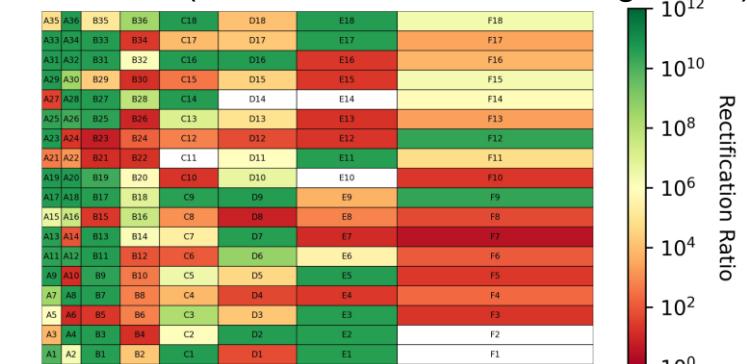
NL2-W2 (base structure, random alignment)



NL2-W3 (300nm anode, random alignment)



NL2-W4 (400nm anode, random alignment)

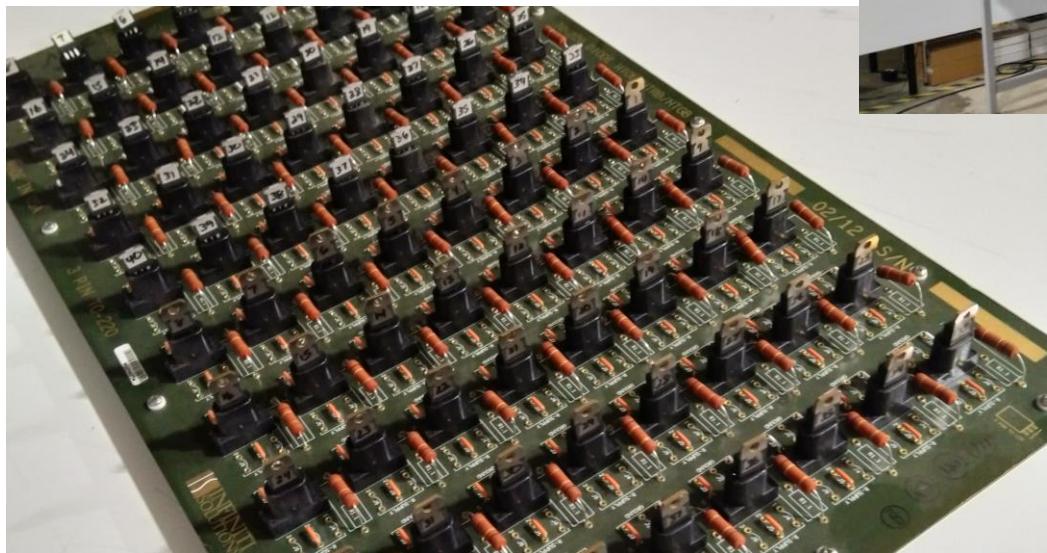


- ON/OFF ratio used for preliminary yield analysis – captures both devices that don't turn on OR don't turn off

Reliability and Failure Analysis

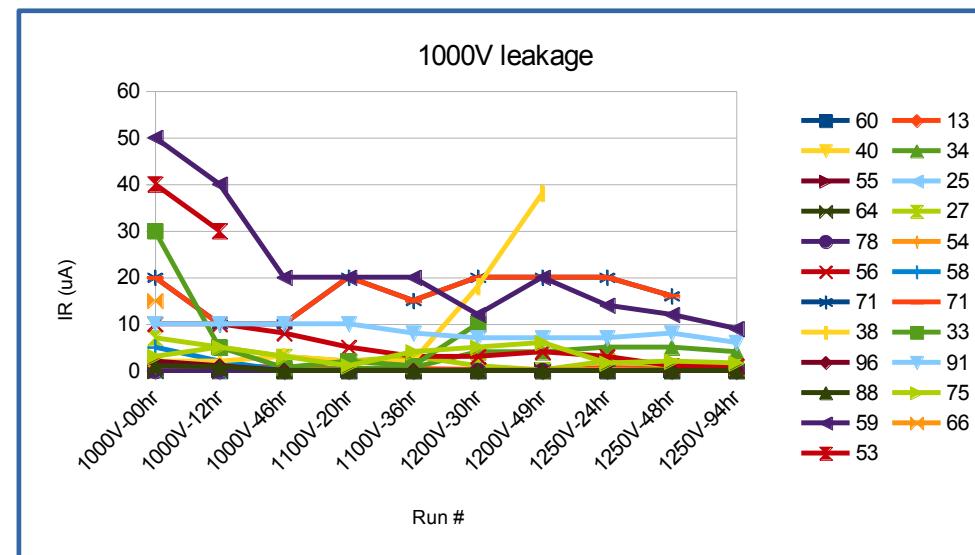
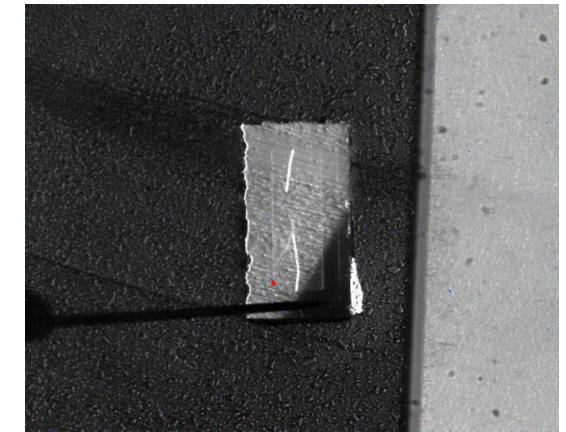
- Extensive vertical GaN reliability and FA effort ongoing

Reliability test ovens and power supplies



Reliability test board

Failure Analysis: Emission Microscopy (EMMI)



High Temperature Reverse Bias leakage current data

- Overview of WBG Power Electronics
- Medium-Voltage Vertical GaN Devices
 - PN Diodes
- Vertical GaN Devices for Electric Vehicles
 - JBS Diodes and MOSFETs

DOE Targets for Electric Vehicle Drivetrains

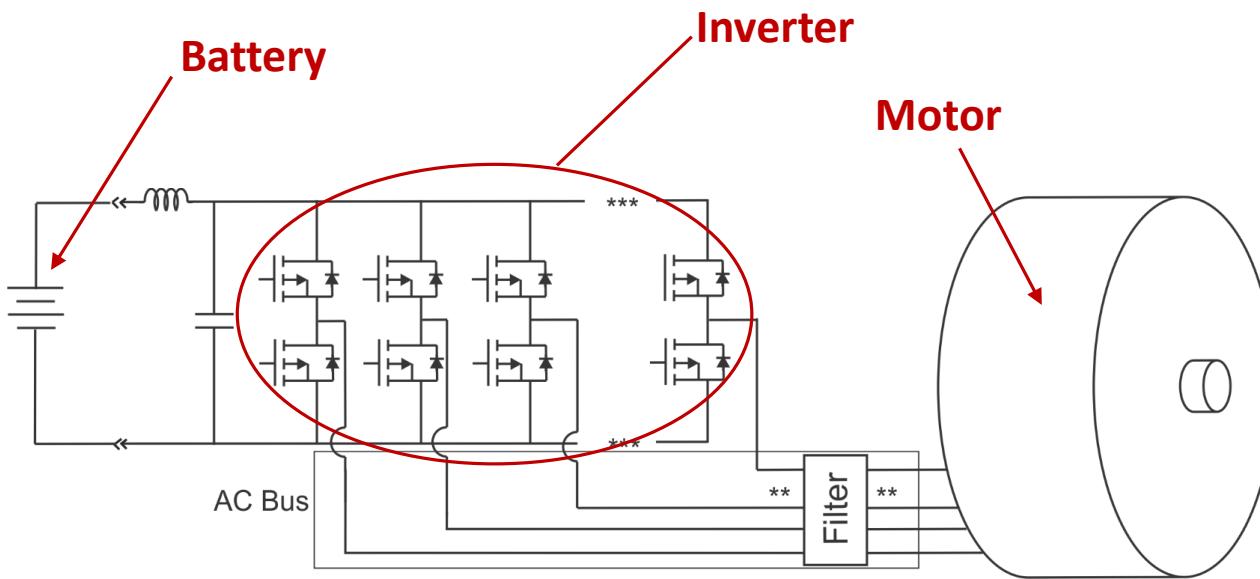
- The Department of Energy has partnered with several automotive and energy companies to create a tentative roadmap for improvements to electric vehicle drives.
- “... EETT has a 2025 power density research target of **33 kW/L for a 100 kW peak system**. While achieving this target will require transformational technology changes to current materials and processes, it is essential for enabling widespread electrification across all light-duty vehicle platforms.”
- 33 kW/L target is for motor plus power electronic drive; PE target is 100 kW/L for 100 kW system
- Reliability and cost targets are also specified

For more information about U.S. DRIVE, please see the U.S. DRIVE Partnership Plan at www.vehicles.energy.gov/about/partnerships/usdrive.html

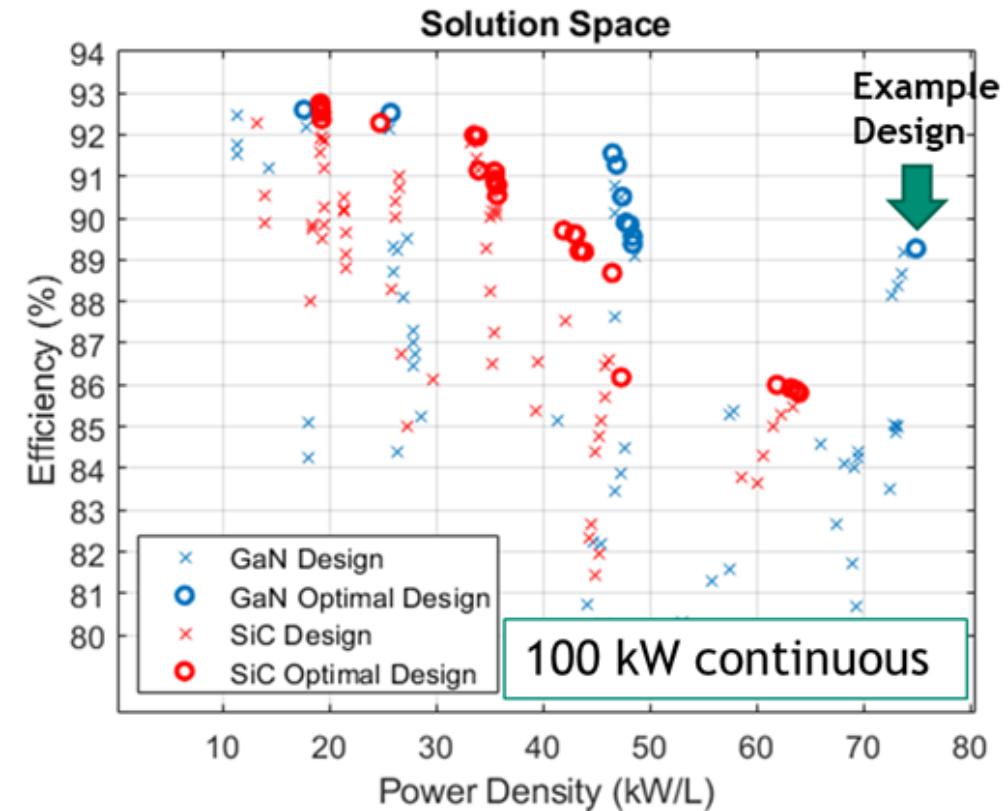


Advantages of Vertical GaN for Electric Vehicles

Electric Drivetrain Schematic



- Inverter and optional boost converter require switch-diode pairs (typical for switch-mode power conversion circuits)
- MOSFET and JBS diode are likely good choices (JBS diode combines best properties of Schottky and PN diodes)



- System-level genetic optimization indicates that vertical GaN diodes may out-perform SiC in terms of efficiency and power density

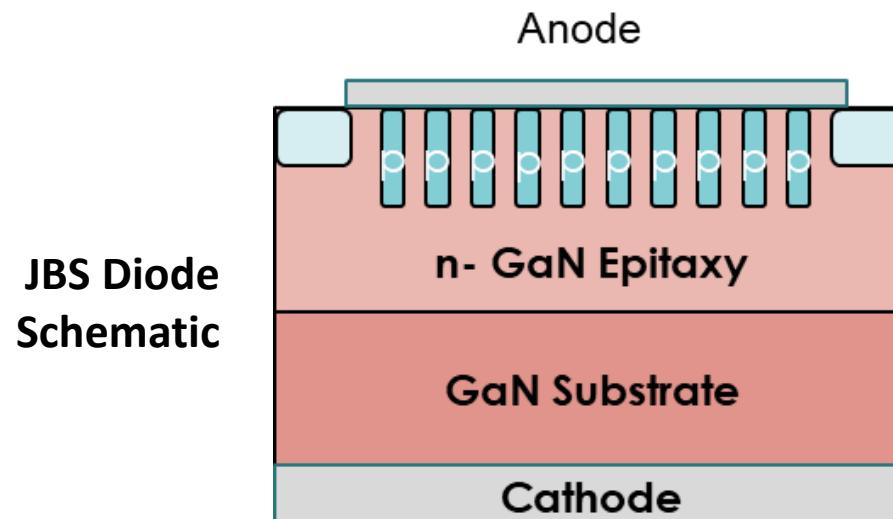
Vertical GaN JBS Diode Development

Fabrication of GaN JBS diodes:

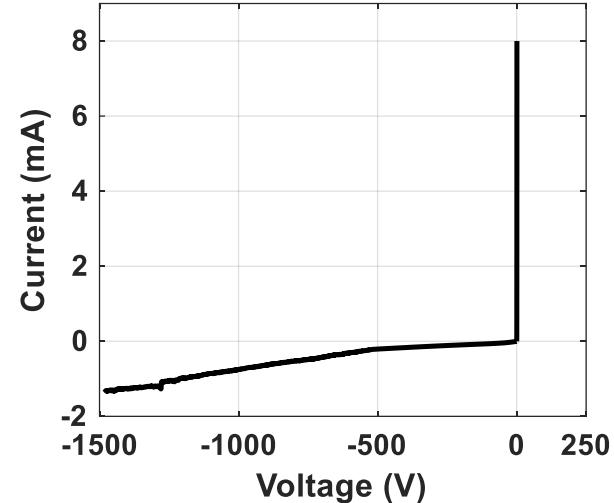
- Etched-and-regrown JBS diode demonstrated
- 1500 V reverse holdoff voltage

Next Steps:

- Exploring regrowth surface pre-treatment strategies to reduce current leakage
- Added JTE to aid in field management and improve reverse breakdown

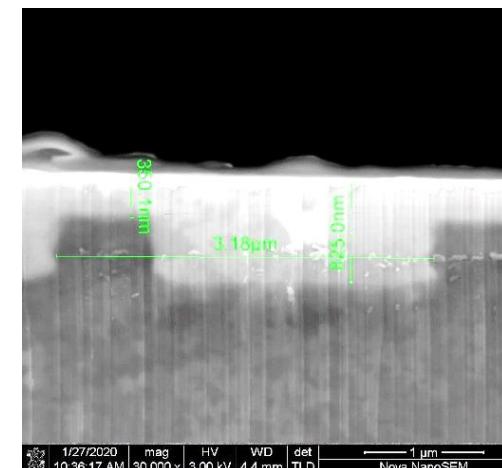


IV curve for gen 1
GaN JBS diode

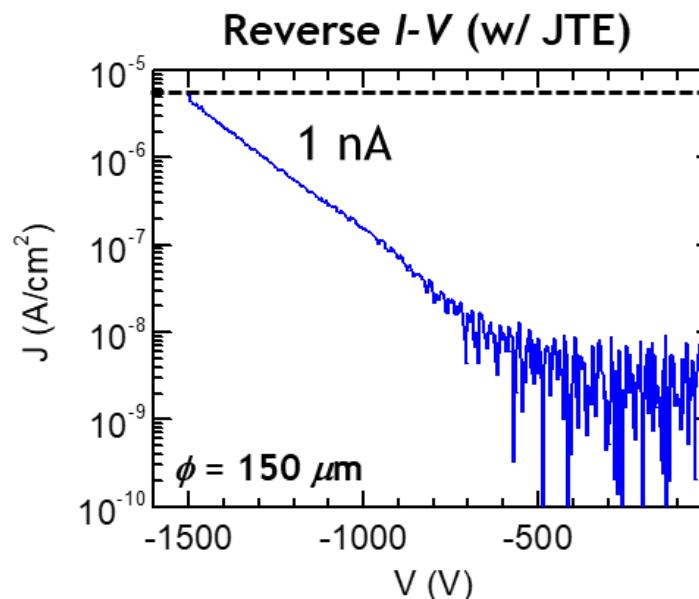
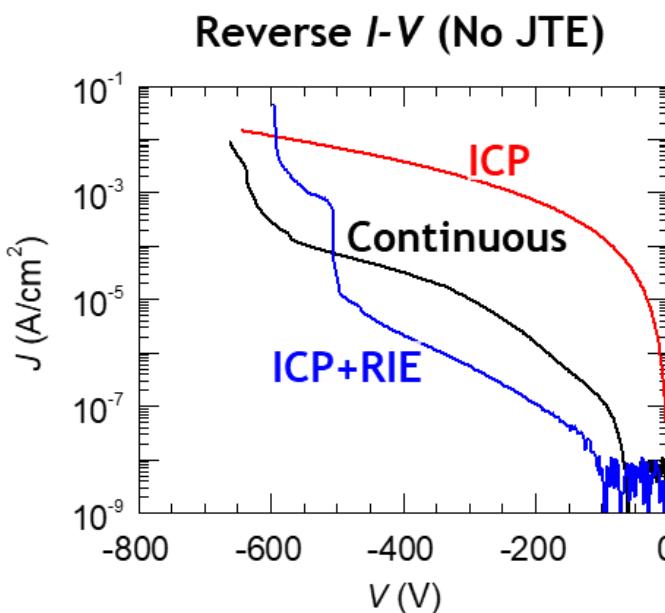
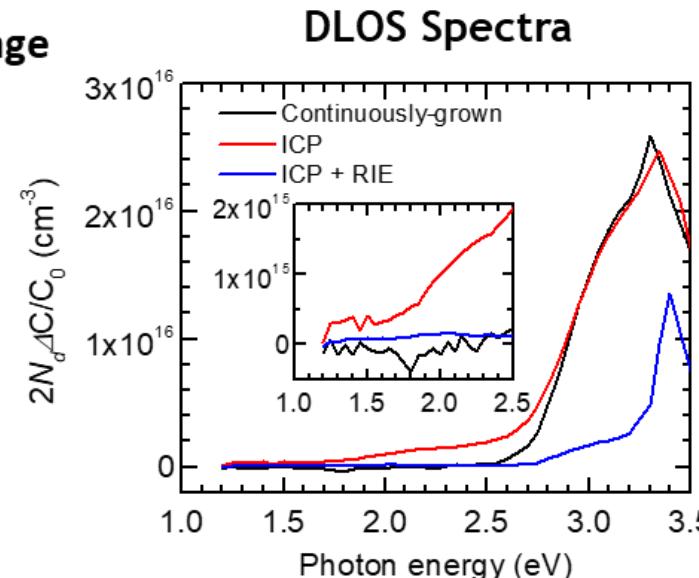
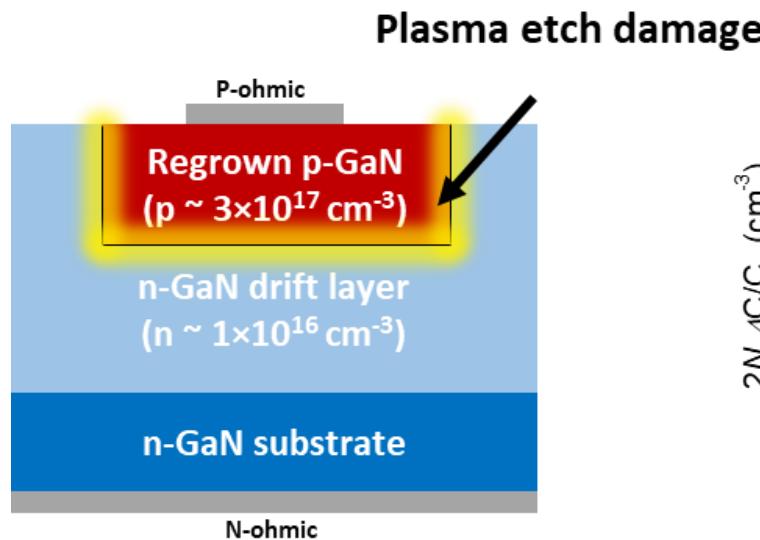


- Low turn-on voltage (consistent with Schottky)
- Low leakage current (consistent with PN junction)
- Confirms JBS operation

Cross-Sectional
SEM of
Regrown PN
Junction

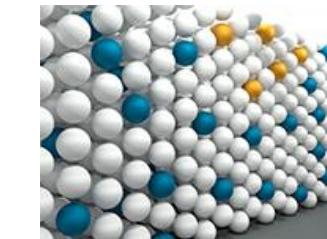


Etch and Regrowth Needed for JBS Diodes



arpa-e

CHANGING WHAT'S POSSIBLE



PNDIODES

- Correlated E_c – 1.9 eV deep level with plasma damage and leakage
- Removed plasma damage with post-ICP RIE step
- Achieved etched-and-regrown diode $> 1.5 \text{ kV}$ and $1.4 \text{ m}\Omega\text{.cm}^2$

Vertical GaN MOSFET Development

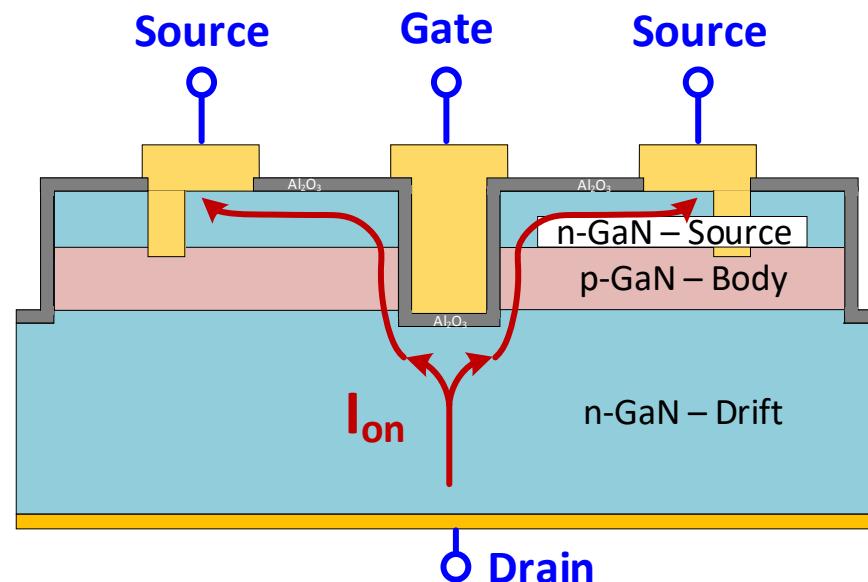
Trench MOSFET key features:

- Selective-area doping not needed for body and source
- Gate on vertical etched GaN sidewall
- High fields at bottom trench corner

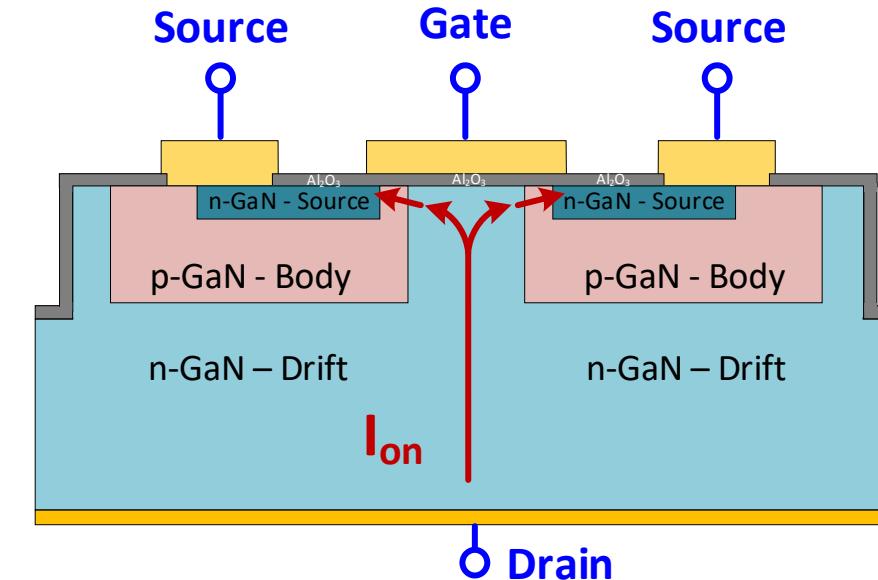
Double-well MOSFET key features:

- Selective-area doping required for body and source
- Gate on planar top surface
- JFET region engineering critical

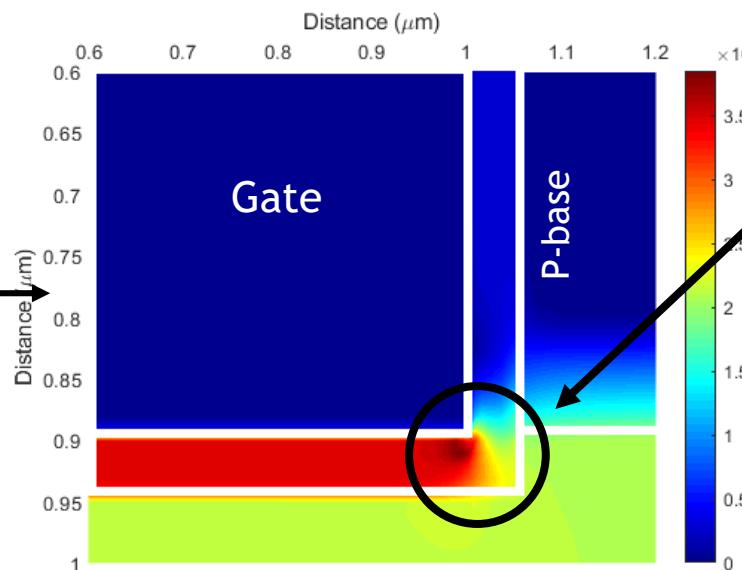
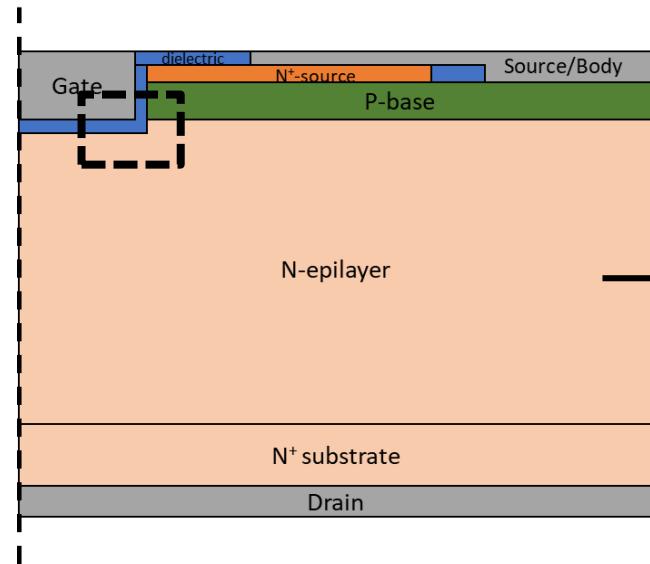
Trench MOSFET



Double-well MOSFET

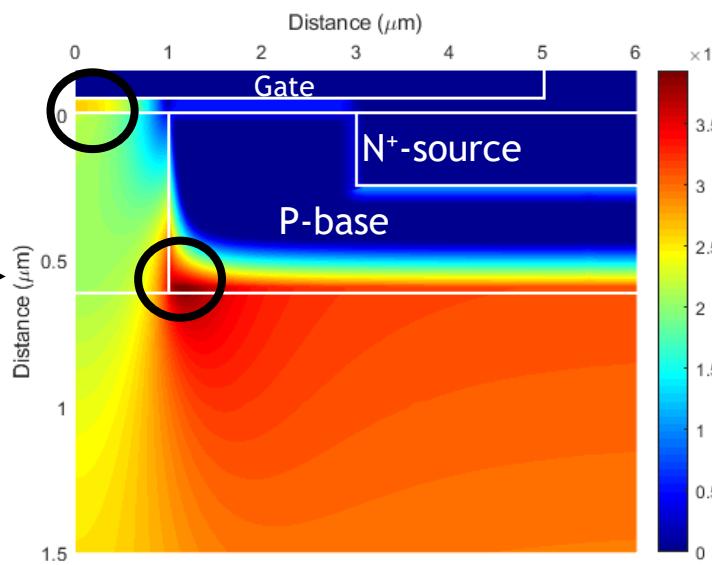
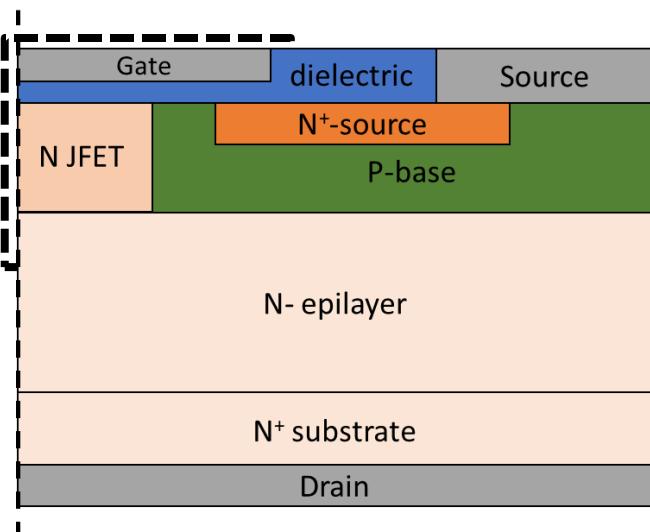


TCAD Simulation of T-MOSFET and D-MOSFET



Field crowding at the corner of the gate elevates electric field in dielectric

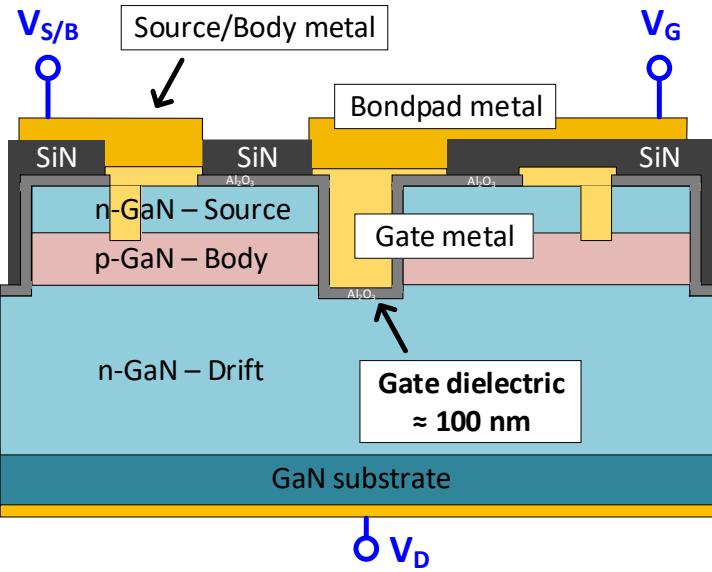
Electric field taken at $V_g=0$ and $V_{DS}=1200$ V



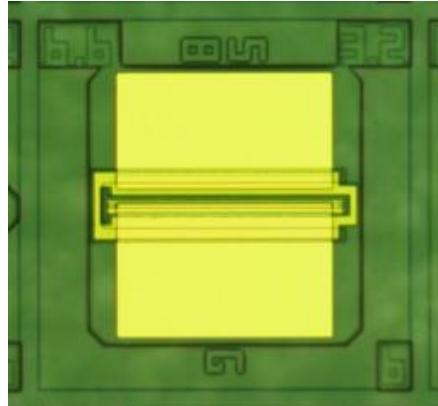
- Large electric field occurs in GaN at corner of JFET region
- Largest dielectric E-field occurs under center of gate

Initial Trench MOSFET Electrical Data

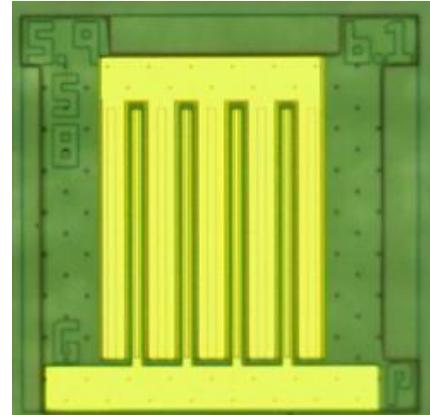
T-MOSFET Diagram



Single-finger

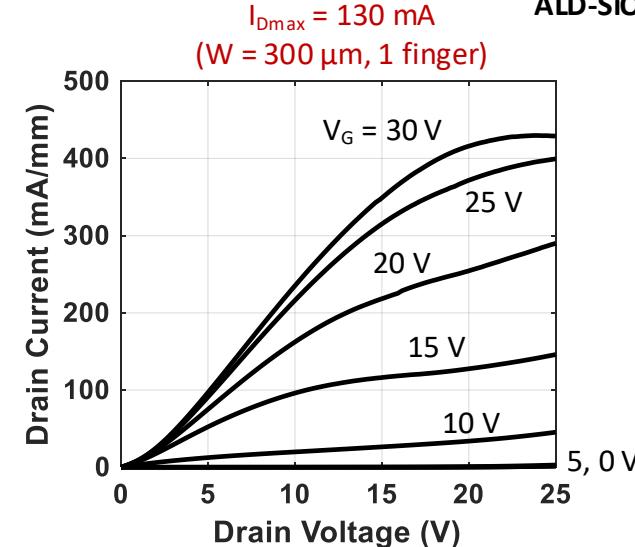


Four-finger

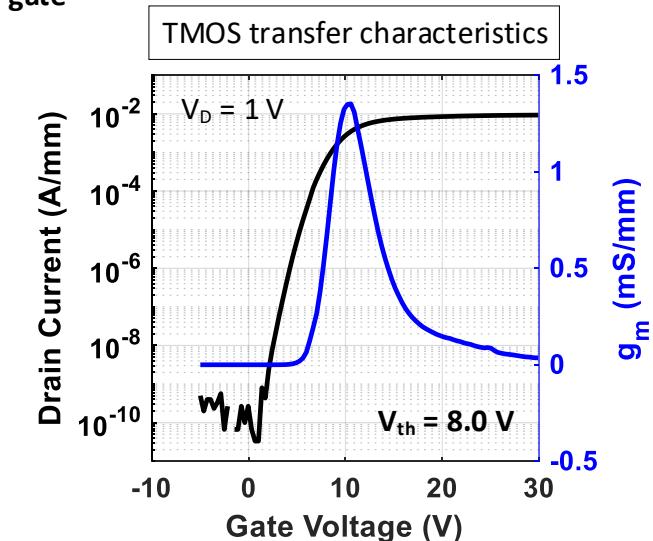


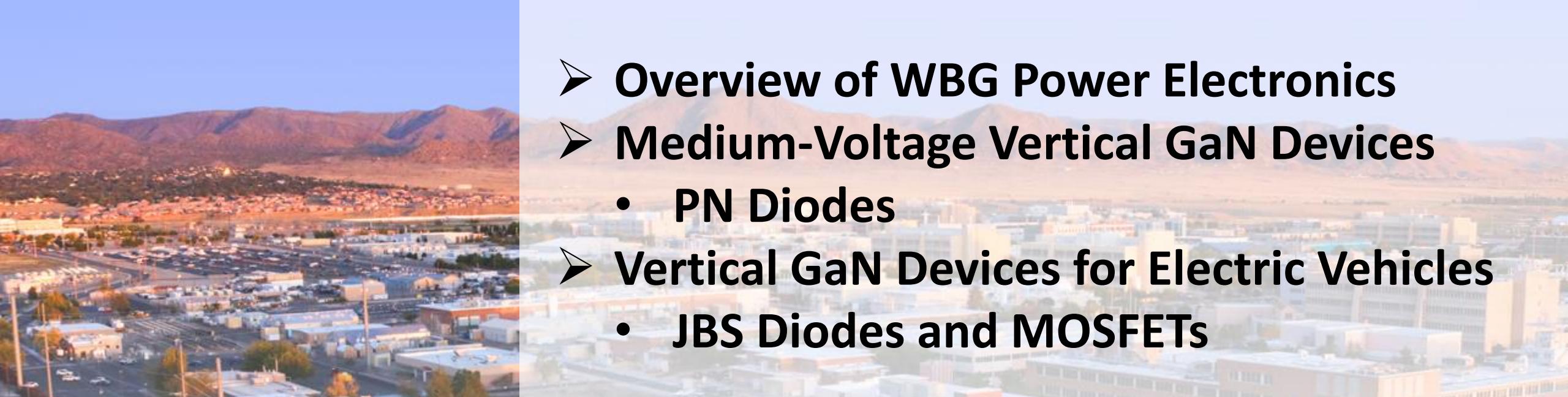
- T-MOSFETs demonstrated
- Devices have a good on/off ratio, $\sim 10^8$
- Positive threshold voltage: ~ 8 V
- Current density ~ 400 mA/mm achieved
 - Single-finger and four-finger devices fabricated

Lot 5: Single Finger MOSFET
ALD-SiO₂ gate



VNA7682C-D: 6.5-4.4





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Questions?
Bob Kaplar: rjkapla@sandia.gov